

GRANIT 2014

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Europe/Paris timezone

Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

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Les Houches



*INFN - Area della Ricerca di Bologna
Biblioteca di Area*



Bologna

Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

Area della Ricerca di Bologna

- Chemistry
- Micro-electronics
- Material science
- Astrophysics
- Agronomy
- Etc.



ISOF: Istituto per la Sintesi Organica e la Fotoreattività'

- New methodologies of organic synthesis
- New photoluminescent organic molecules: synthesis and assembling into functional nanostructures
- Bio-organic processes
- New materials and nanotechnology

- Supramolecular systems
- Photochemistry and catalysis
- Radical reaction chemistry
- Macromolecular systems

Nanochemistry Lab

Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

WHY?

WHAT?

HOW?

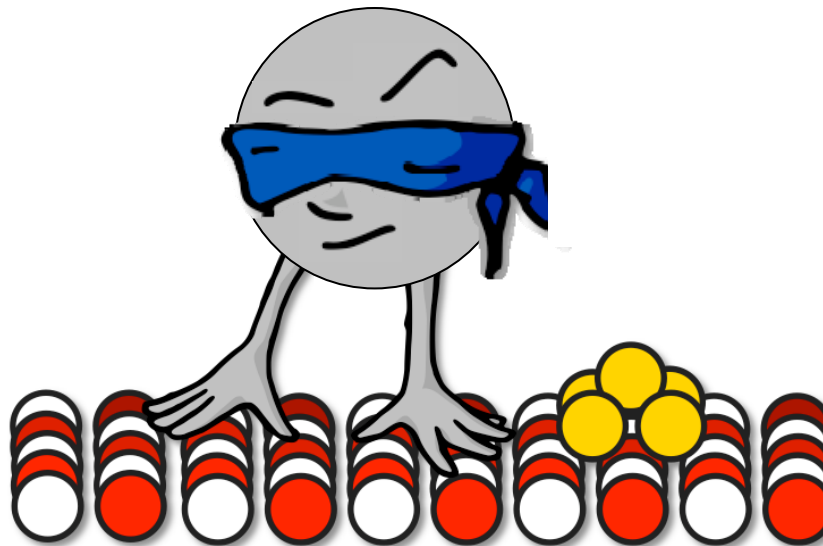


WHY?

de Broglie wavelength (λ_{dB})

Temperature (K)	E (meV)	Velocity	λ (nm)
-----------------	---------	----------	----------------

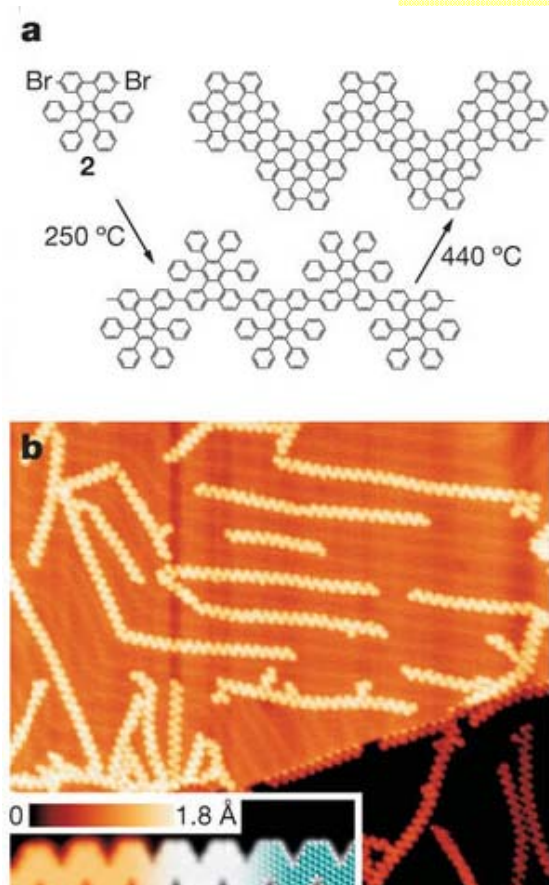
UCNs feel nanoscale world



Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

WHAT?

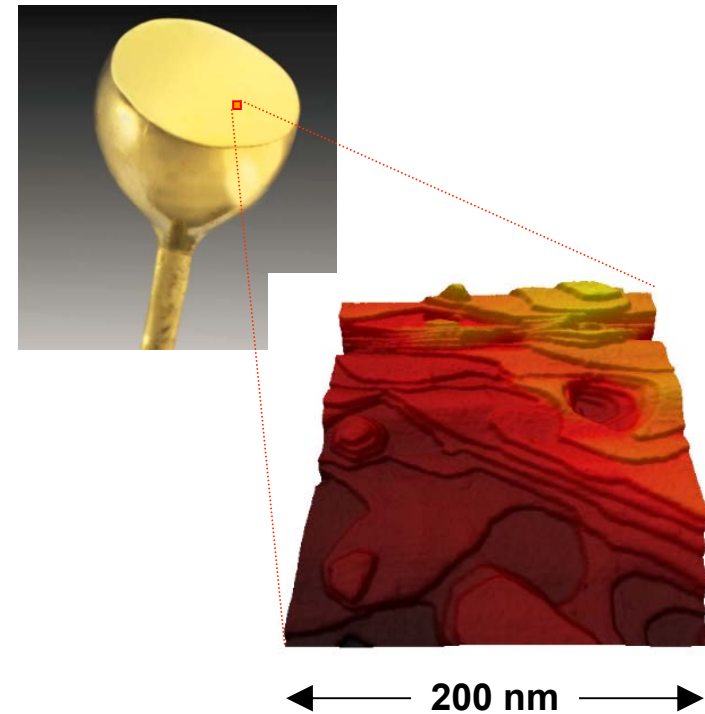
Nano-objects



Cai J. et al., Nature 466, 470–473 (2010)

Nanoscale

Nanoscaled-objects

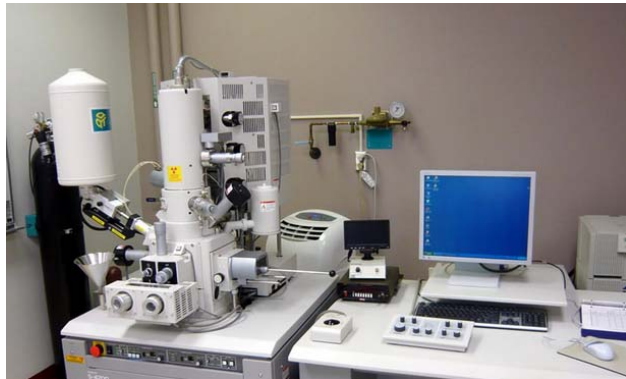


http://www.specs.de/cms/upload/PDFs/AppINotes/AFM/AN_NCAFM_AtomicResolution_Au111.pdf

Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

HOW?

Electron microscopy (TEM, SEM)



Lat Res: 1 Å



Vacuum
(10^{-9} mbar)

Scanning Probe Microscopy (SPM)

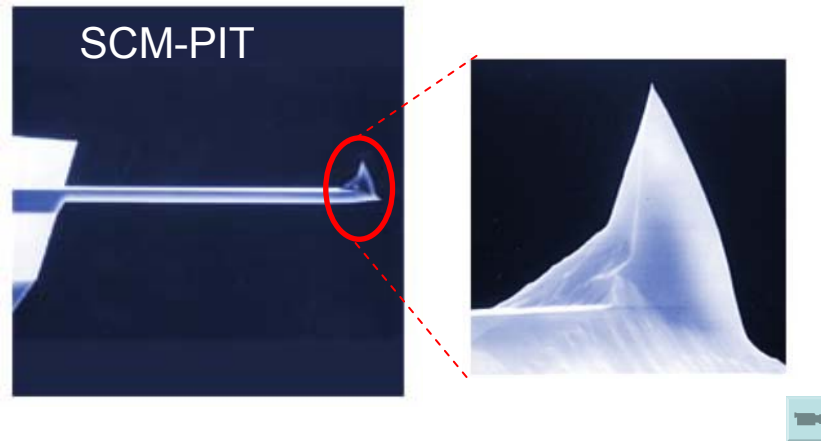


Lat Res: 1 Å – 1 nm

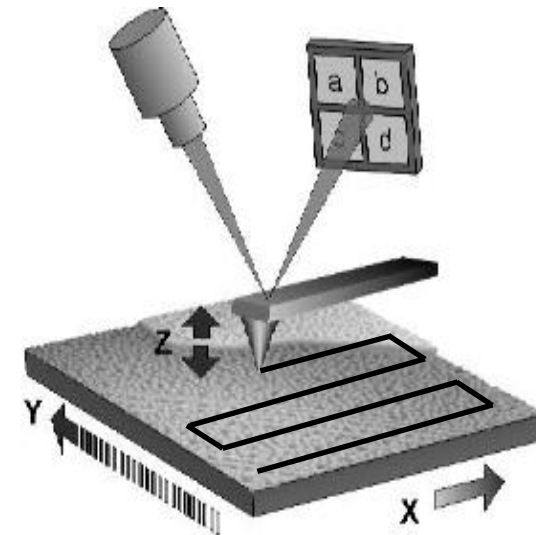


Slow technique
(μm^2 / min)

SPM technique, image acquisition



- Tip at free end of a flexible cantilver
- Deflection due to the tip-sample forces
- Cantilever raster scanned over the sample
- Measurement of the Z-adjustment



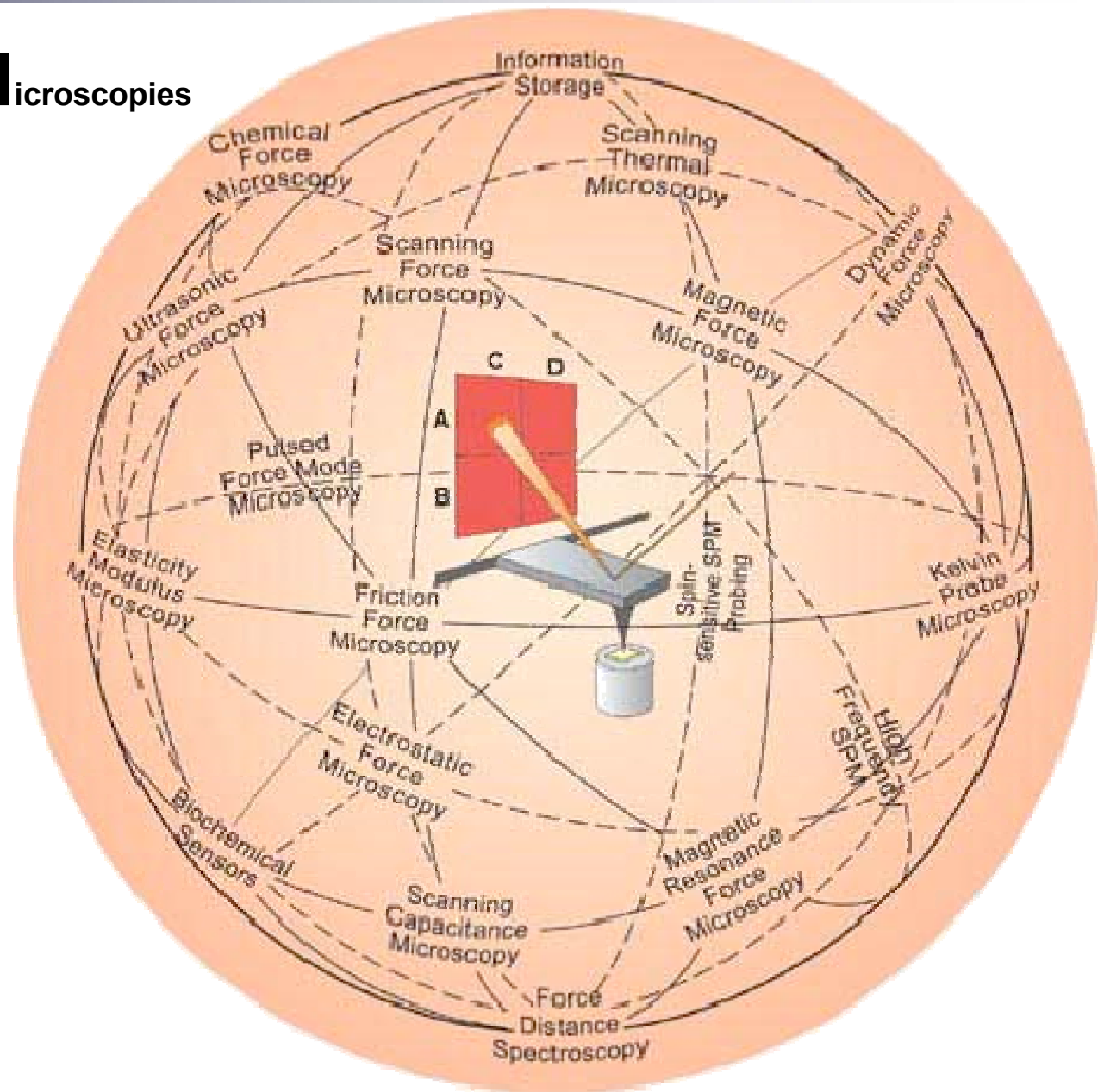
Surface topography
 $n \times m$ matrix

Scanning PROBE Microscopies

FORCE

Interactions:

- Van der Waals
- Electrostatic
- Magnetic
- Capacitive
- Frictional
- etc...



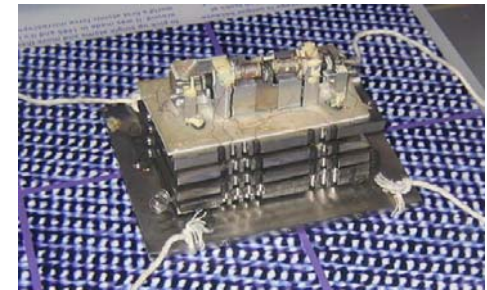
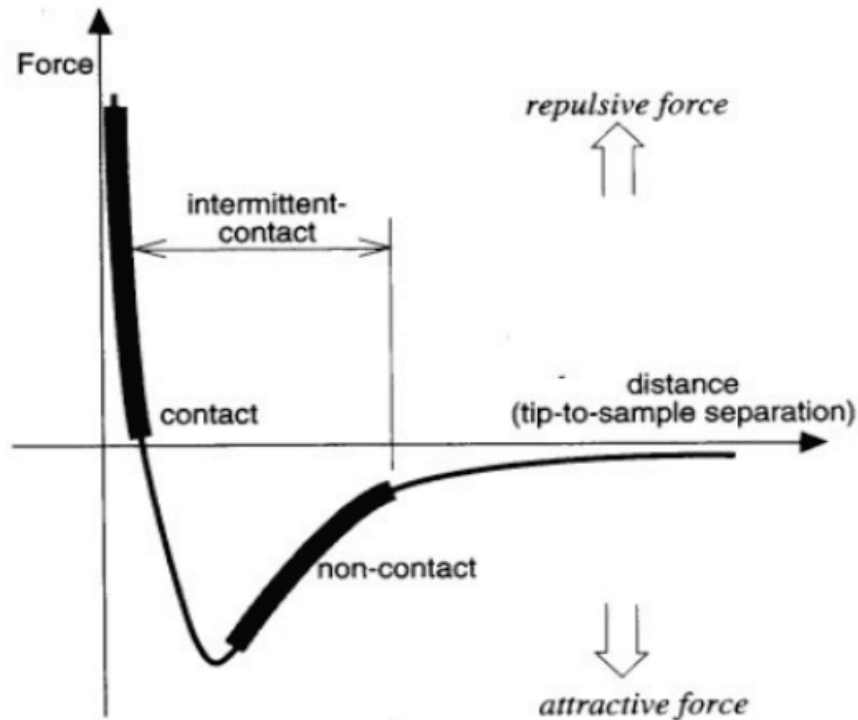
Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

1986. First AFM microscope

Gerd Binnig, Calvin Quate, Christoph Gerber

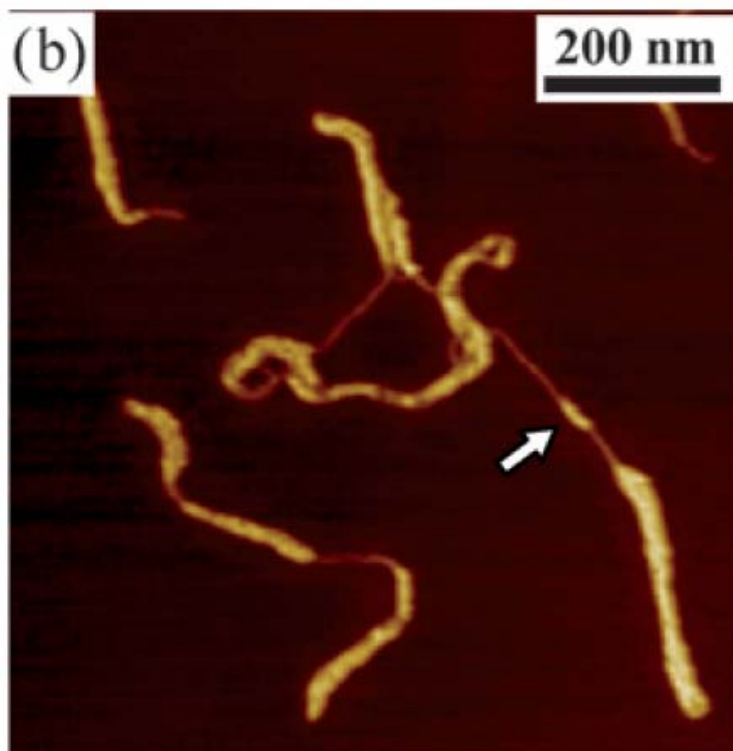
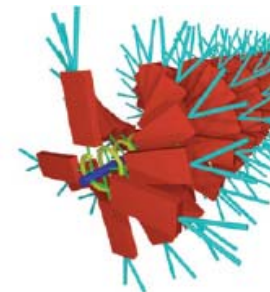
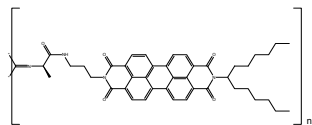
Atomic Force Microscopy (AFM)

Probe = vdW FORCE

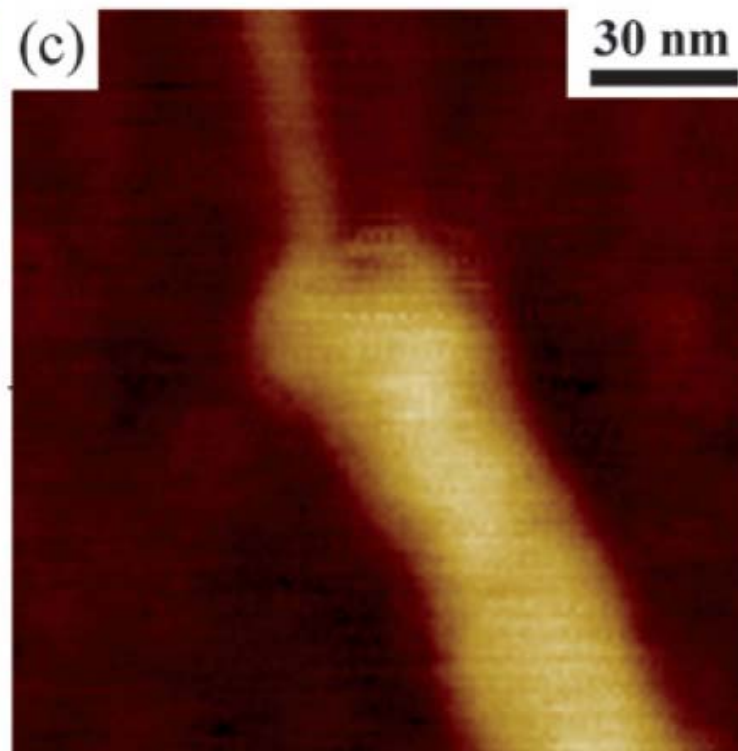


Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

AFM, high resolution in air



Z range = 5 nm



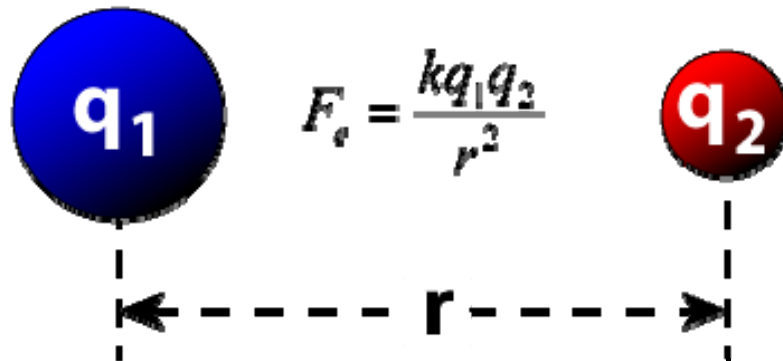
Z range = 5 nm

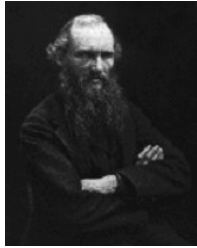
1991. First KPFM microscope

N Nonnenmacher et al., *APL* **58**, 2921

Kelvin Probe Force Microscopy (KPFM)

Probe = Electrostatic FORCE





William Thomson,
a.k.a. Lord Kelvin, 1898

Kelvin Probe FORCE Microscopy

Work function measurement
of metallic and semi-conductive samples

Vibrating capacitor
Zisman method (1932)

$$i(t) = (V - V_{cpd}) \frac{dC}{dt}$$

U.S. Patent

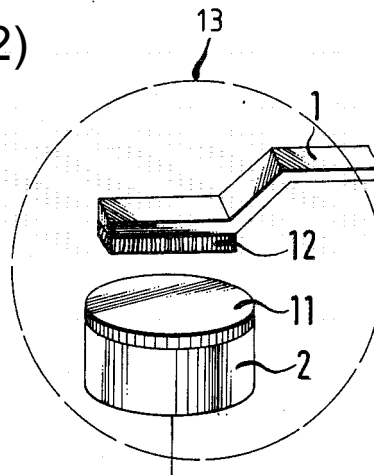


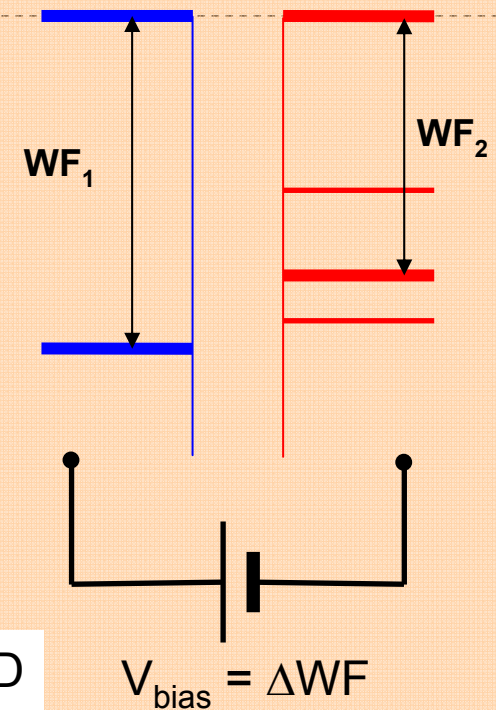
FIG. 1A

WF

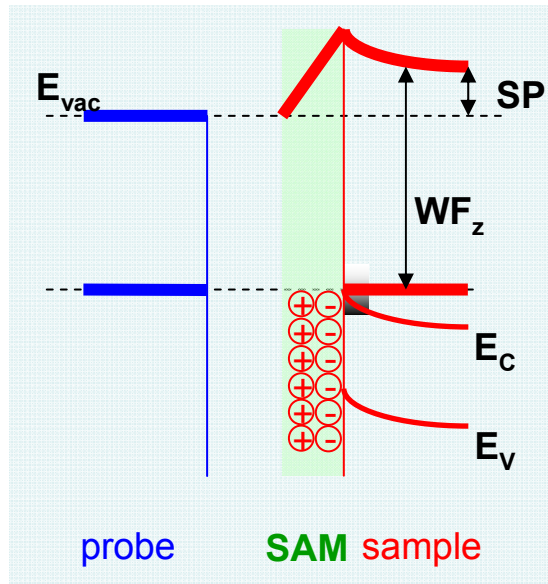
F₂

a.k.a. CPD

a.k.a. SP



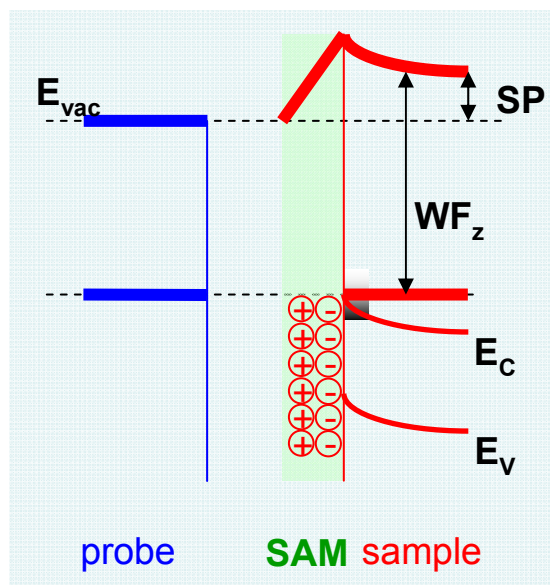
Kelvin Probe FORCE Microscopy



Measurements on SAM and thin film

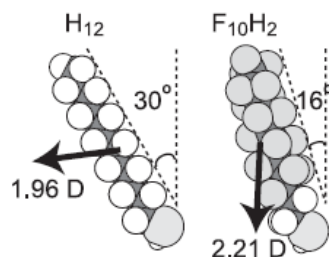
- tip-sample work function difference (ΔWF)
- thin film dipole (μ_{SAM})
- band-bending
- interface bonding
- fixed charges

Kelvin Probe FORCE Microscopy

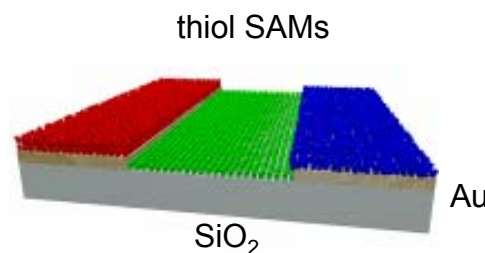


Measurements on SAM and thin film

- tip-sample work function difference (ΔWF)
- thin film dipole (μ_{SAM})
- band-bending
- interface bonding
- fixed charges



Alkanethiol (H_{12})
Fluoroalkaneethiol ($F_{10}H_2$)



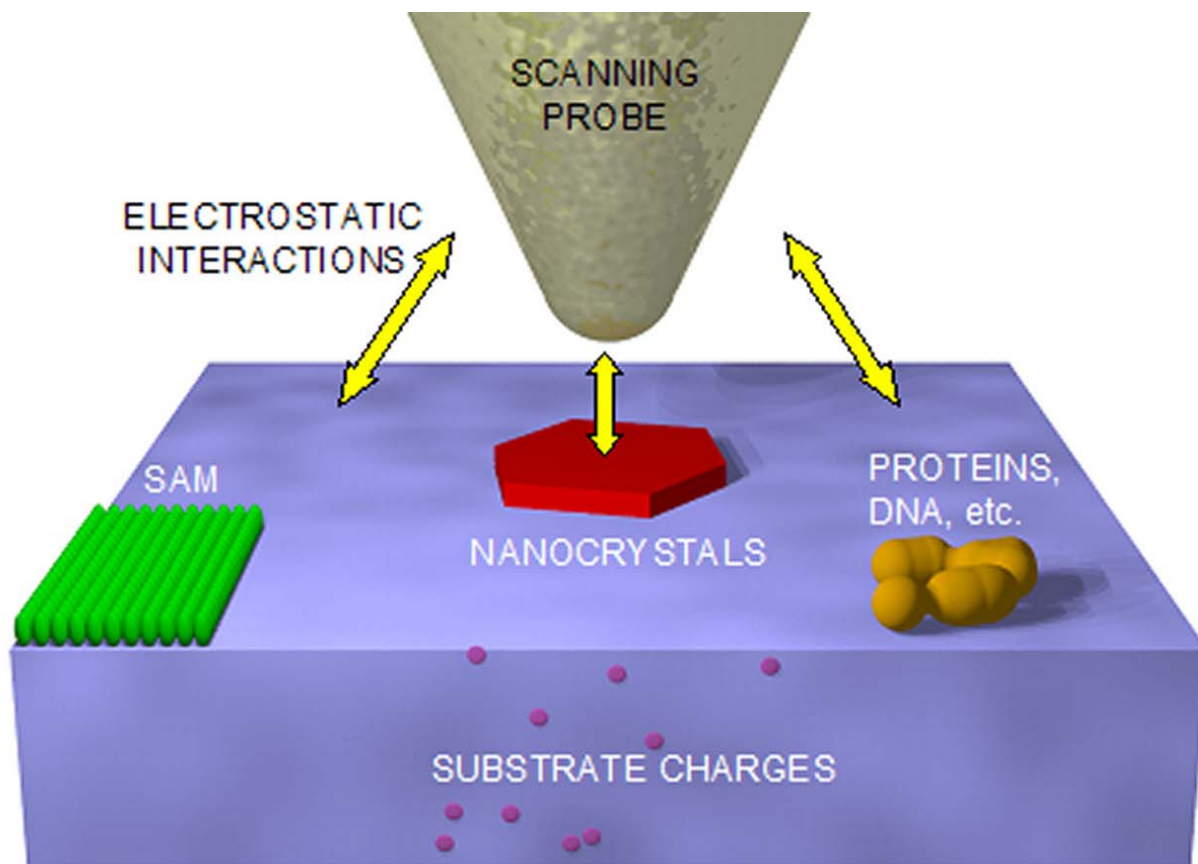
$$SP_{SAM/Au} = WF_{Au} + A \cdot \mu_{thiol,\perp} / \epsilon_{thiol}$$

[KP] Alloway D.M. et al. *Journ. Phys. Chem. B* **107** (2003), 11690-11699

[KPFM] Saito N. et al., *Surf. Interface Anal.* **34** (2002), 601-605

[KPFM] Liscio A. et al., *Adv. Mat.* **22** (2010), 5018-5023

Kelvin Probe FORCE Microscopy

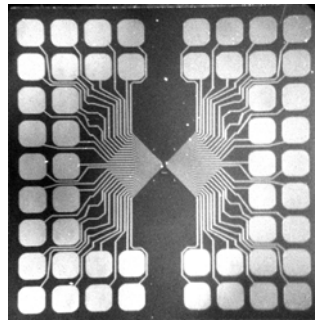


AFM setup

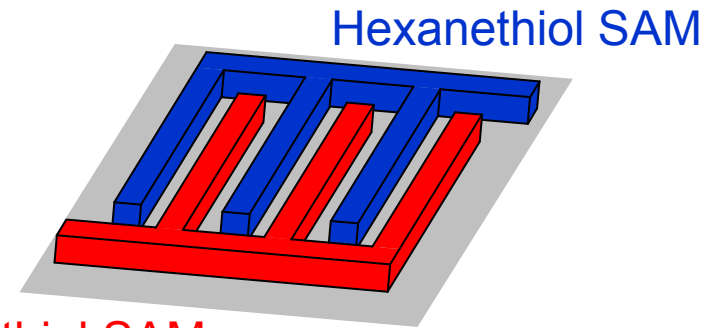
- Metals
- Semiconductors
- Thin insulators

Morphology &
Surface Potential
simultaneously

Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

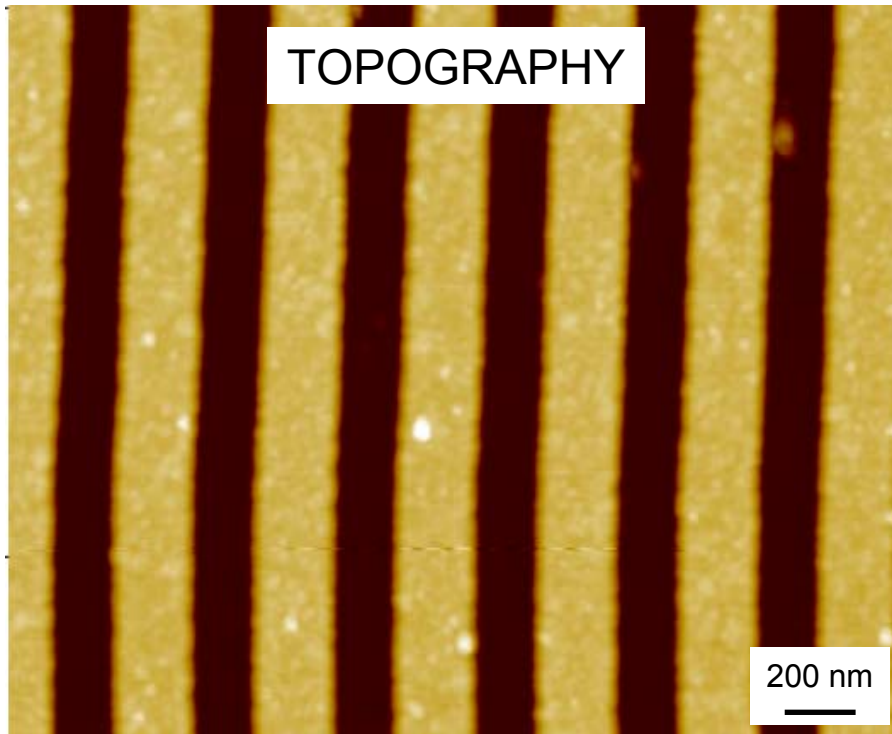


1 mm



Dodecanethiol SAM

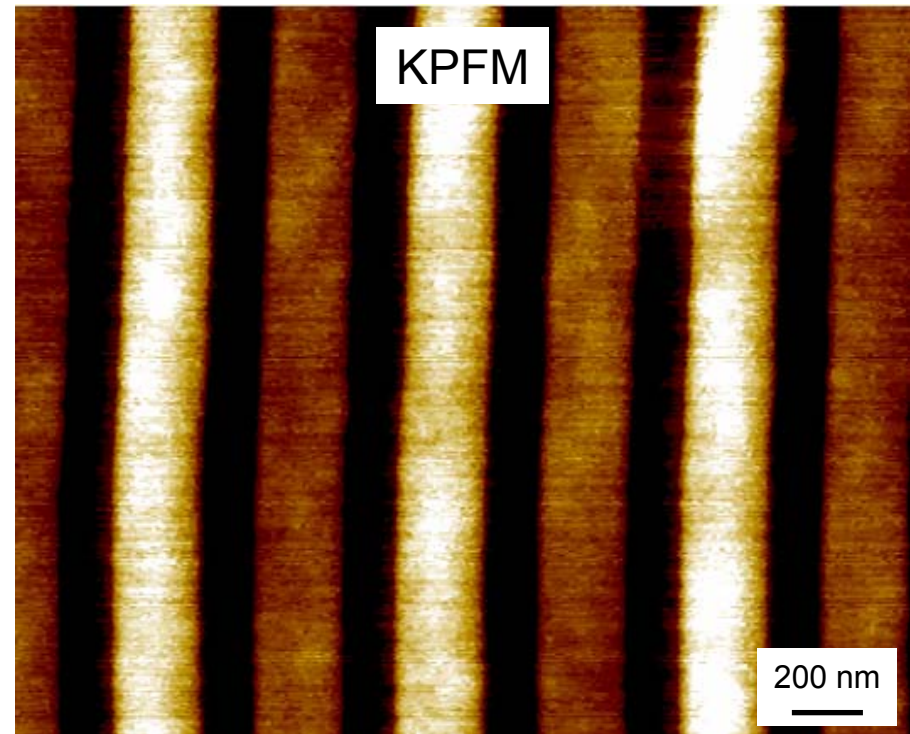
TOPOGRAPHY



200 nm

Z range = 50 nm

KPFM



200 nm

Z range = 40 mV

Theory of KPFM

1.
$$F_{el} = -\frac{1}{2} \frac{\partial C}{\partial z} (V_{tip} - V_{sample})^2 = F_0 + F_\omega + F_{2\omega}$$

2.
$$F_0 = -\frac{1}{2} \frac{\partial C}{\partial z} \left[(\Delta SP - V_{DC})^2 + \frac{V_{AC}^2}{2} \right]$$

3.
$$F_\omega = -\frac{\partial C}{\partial z} (\Delta SP - V_{DC}) \cdot V_{AC} \sin(\omega \cdot t)$$

4.
$$F_{2\omega} = \frac{1}{4} \frac{\partial C}{\partial z} V_{AC}^2 \cos(2\omega \cdot t)$$

$$V_{tip} = V_{DC} + V_{AC} \sin(\omega \cdot t)$$

$$V_{sample} = V_0 + \Delta SP$$

Theory of KPFM

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$$F_{el} = -\frac{1}{2} \frac{\partial C}{\partial z} (V_{tip} - V_{sample})^2 = F_0 + F_\omega + F_{2\omega}$$

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$$V_{sample} = V_0 + \Delta SP$$

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$$F_{2\omega} = \frac{1}{4} \frac{\partial C}{\partial z} V_{AC}^2 \cos(2\omega \cdot t)$$

$$F_\omega = 0 \Rightarrow \Delta SP = V_{DC}$$

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$$V_{sample} = V_0 + \Delta SP$$

$$4. \quad F_{2\omega} = \frac{1}{4} \frac{\partial C}{\partial z} V_{AC}^2 \cos(2\omega \cdot t)$$

$$F_\omega = 0 \Rightarrow \Delta SP = V_{DC}$$

Metallic samples

$$\Delta SP = WF_{sample} - WF_{tip}$$

Monolayer (few nm)

$$\Delta SP = WF_{sub} + \mu_{film} / \epsilon_r - WF_{tip}$$

Semiconductive films (< 100 nm)

$$\Delta SP = WF_{sub} + WF_{film} + surf \text{ dipoles} + band \text{ bending} + \dots$$

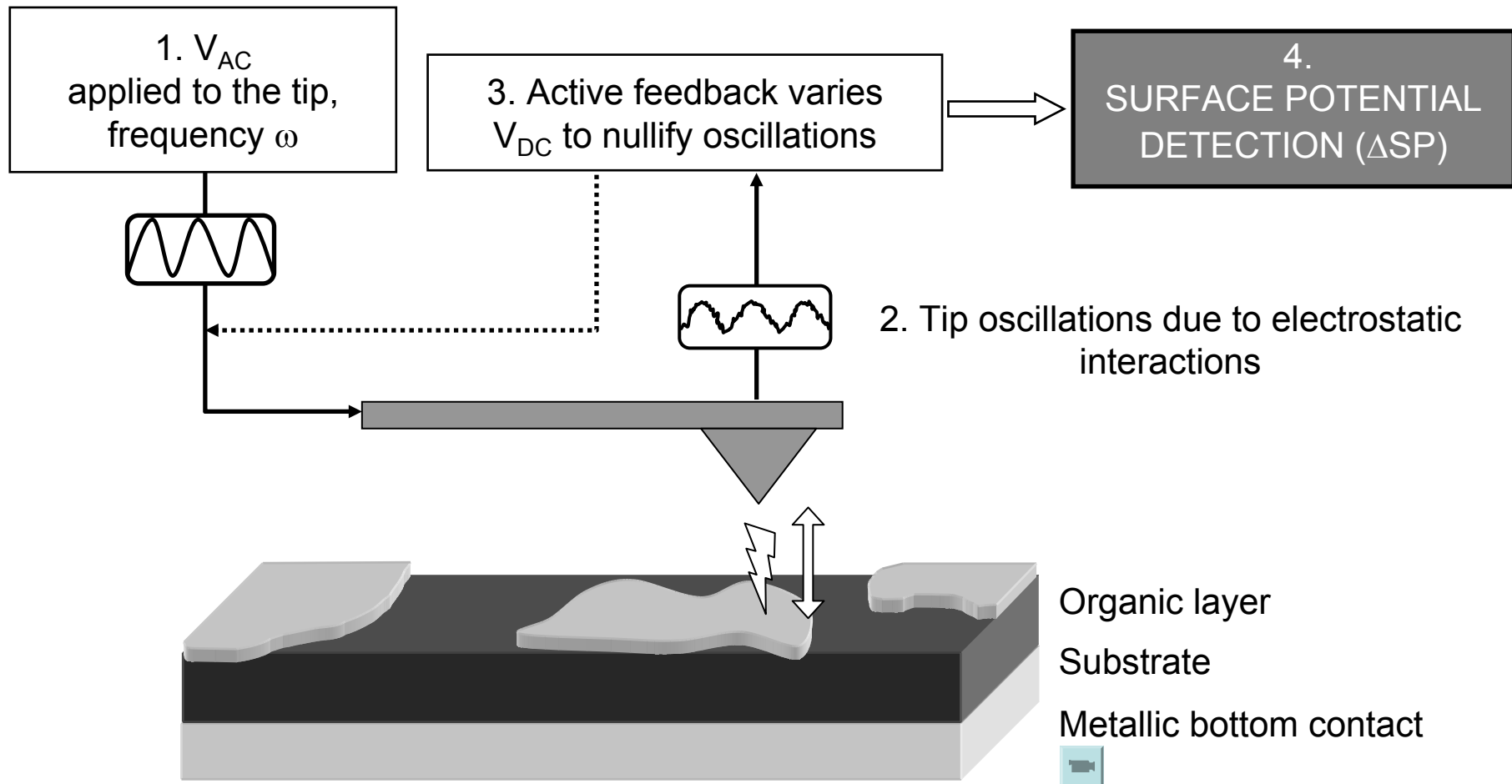
Dielectrics thick films (> 100 nm)

$$\Delta SP = surf \text{ dipole layer} + charge \text{ density}$$

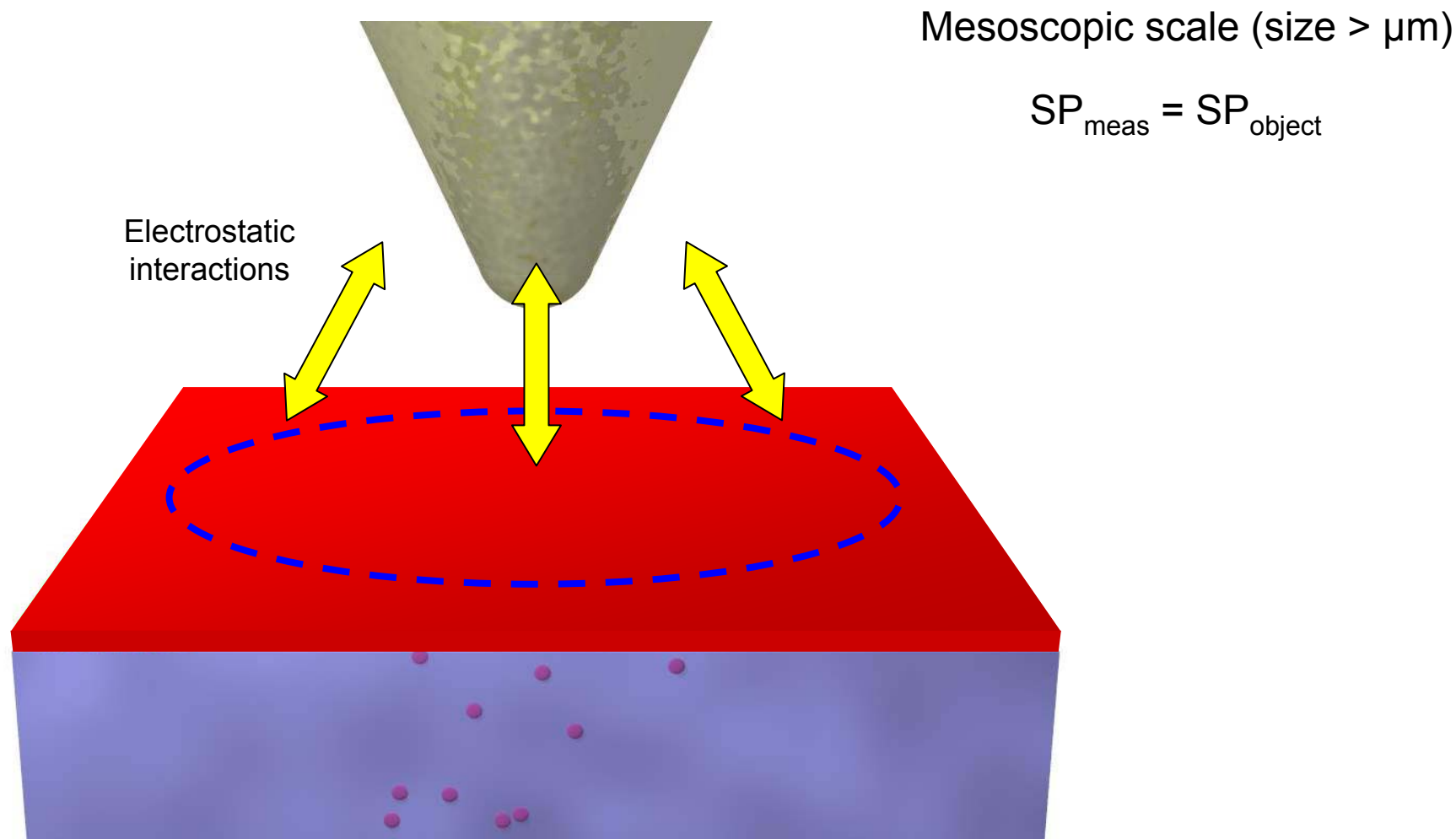
Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

KPFM

Vibrating capacitor, essential features

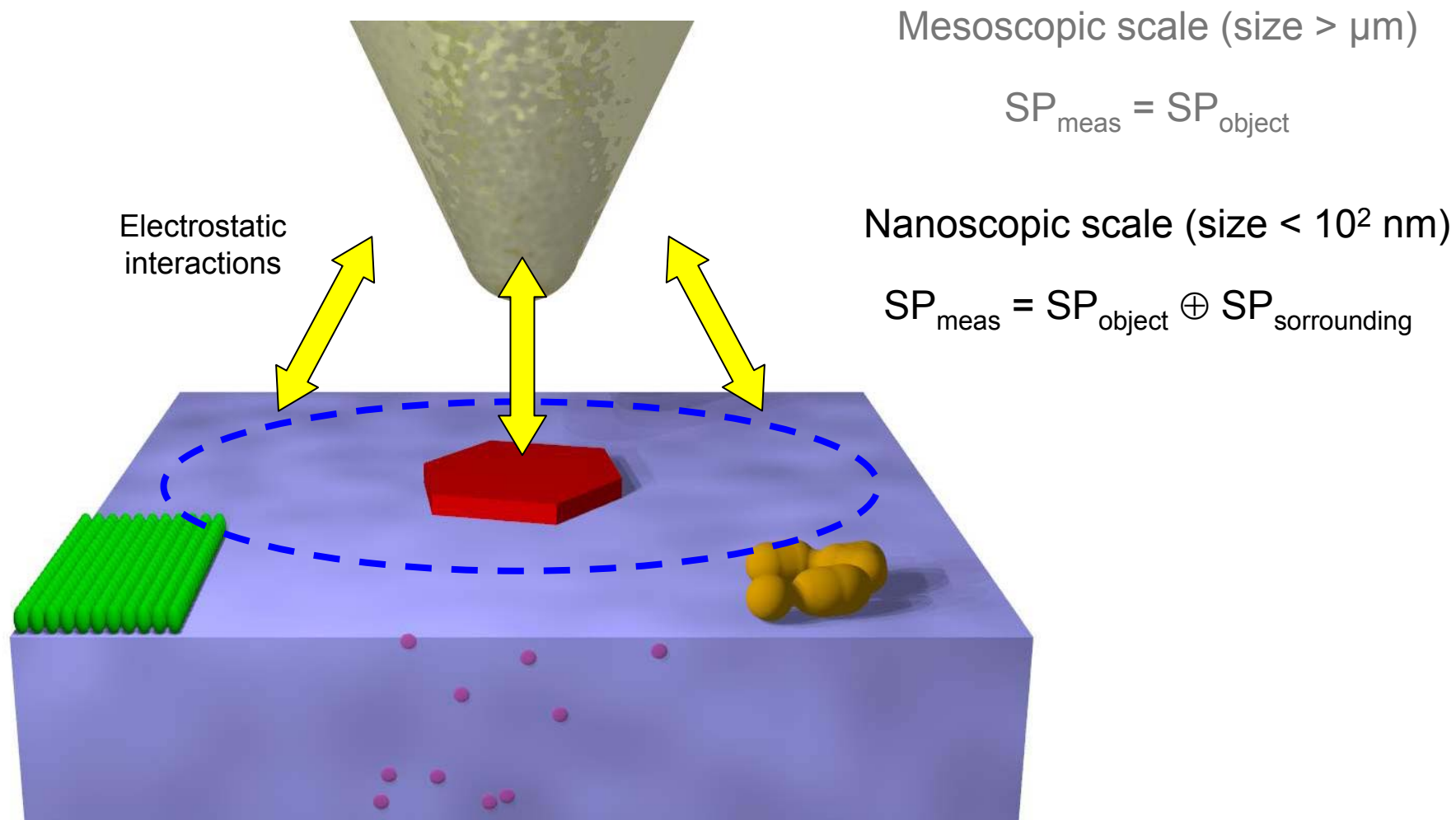


Going into the nanoscale...



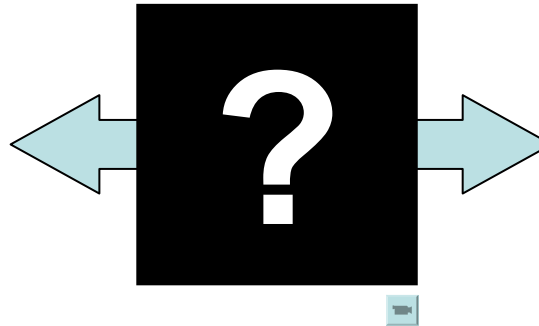
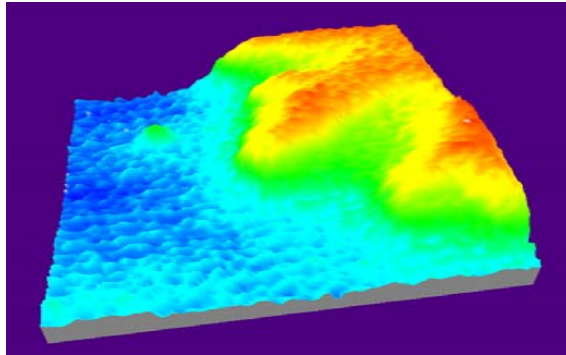
Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

Going into the nanoscale...

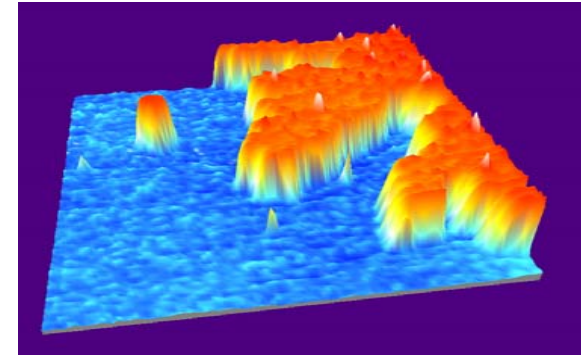


Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

Measured KPFM image

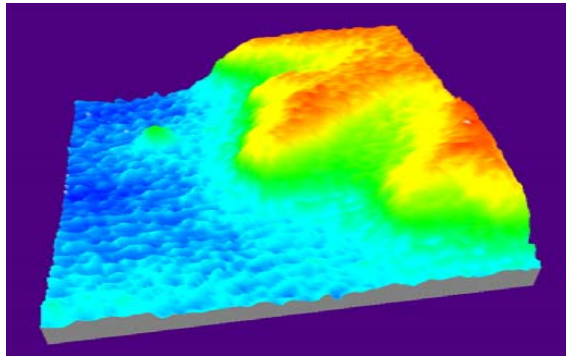


“Real” KPFM image

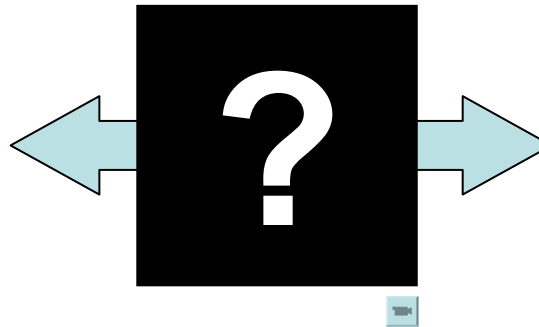
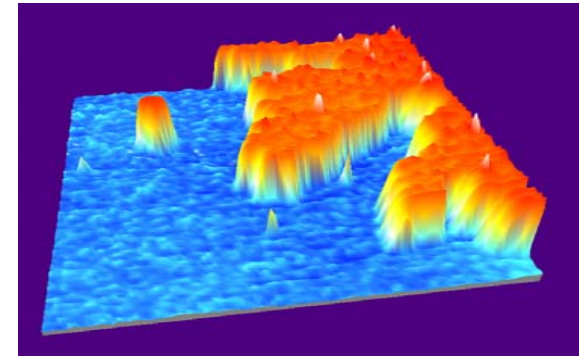


Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

Measured KPFM image



“Real” KPFM image



Transfer function representation

$$SP_{meas}(r_{//}) = \int_{surface} dr'_{//} \int_0^{\infty} \Gamma(r'_{//} - r_{//}, z') \cdot SP_0(r'_{//}, z') dz'$$

$$\Gamma(r'_{//} - r_{//}, z') \propto \lim_{\Delta r'_{//}, \Delta z' \rightarrow 0} \frac{|E(r'_{//} - r_{//}, z')|^2}{W(\Delta r'_{//}, \Delta z')}$$

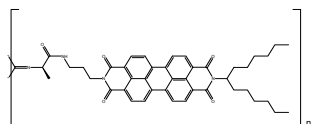
E electric field

W electrostatic energy

Artifacts are mainly due to the tip-sample electrostatic interactions

Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

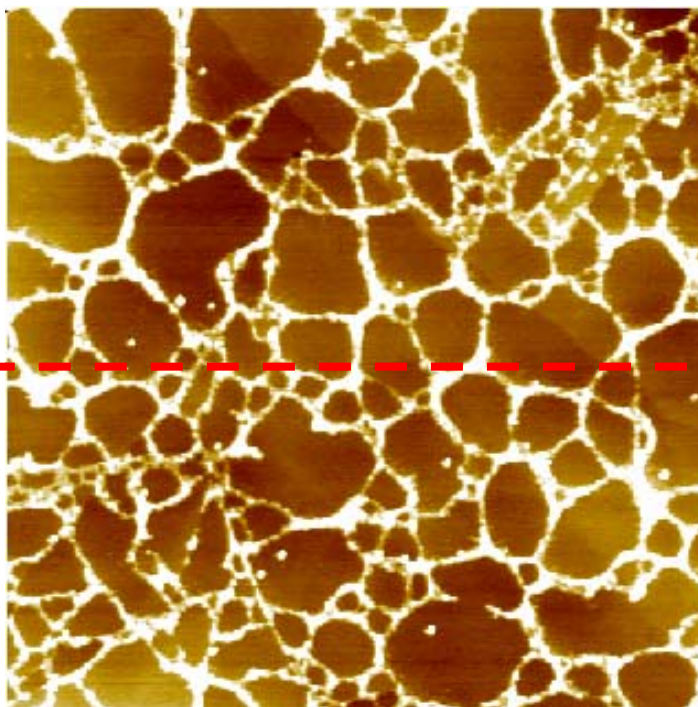
Effect of tip-sample distance (d) in AFM and KPMF images



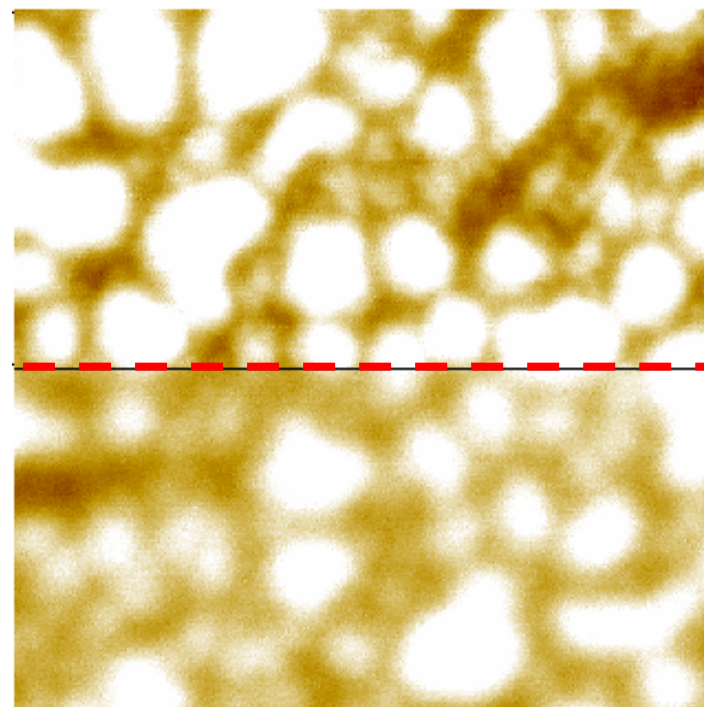
AFM

KPFM

$d = 15 \text{ nm}$



$d = 60 \text{ nm}$



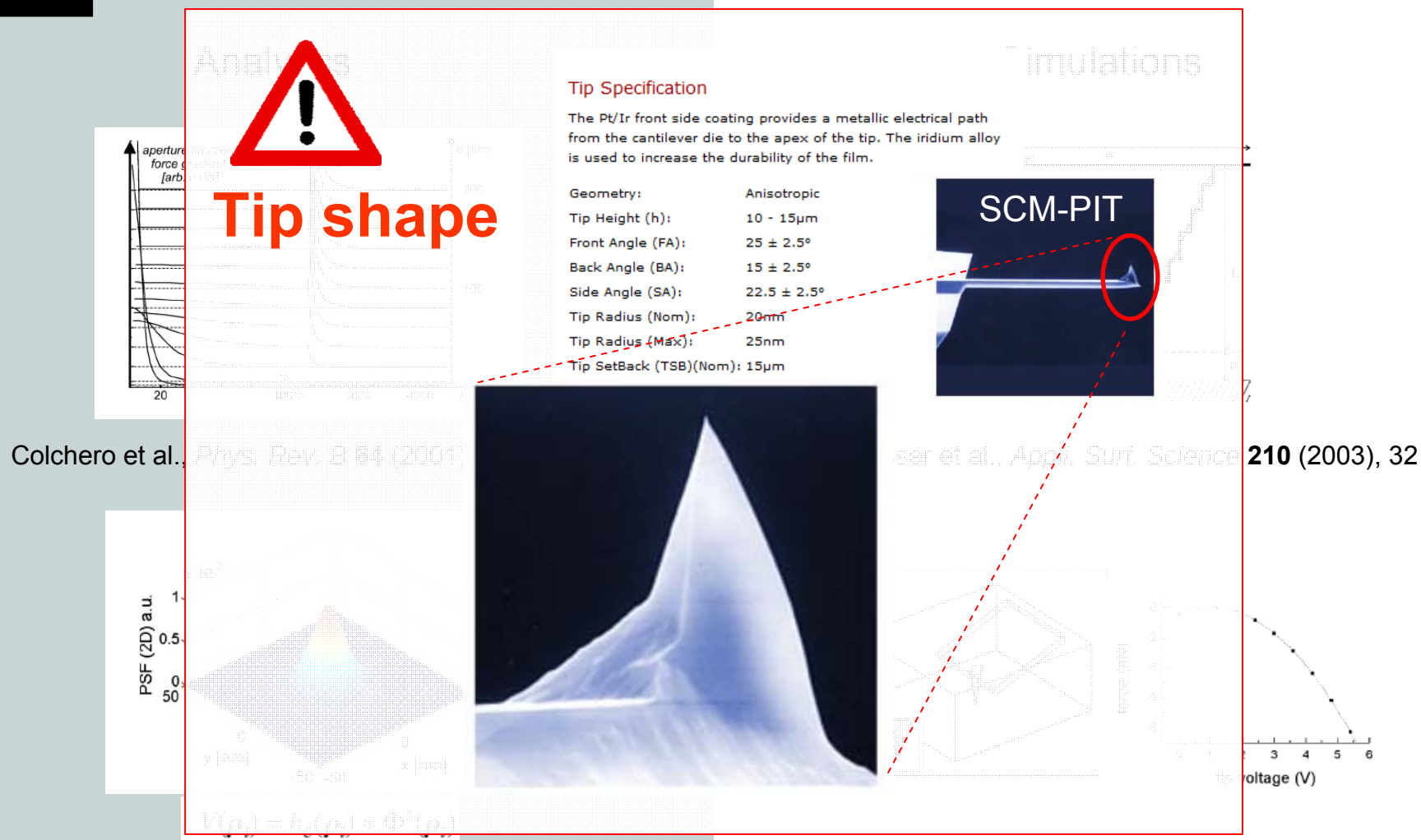
Size: $5.12 \times 5.12 \mu\text{m}^2$
Z-range: 4 nm

Size: $5.12 \times 5.12 \mu\text{m}^2$
Z-range: 100 mV

Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

?

Models used to describe the tip-sample geometry



Γ : an operative definition

1. SP broadening
or simplified geometry



2. $\Gamma(r_{//}, z)$

3. $SP_{meas} = \Gamma \otimes SP_{real}$

Γ : an operative definition

1. SP broadening
or simplified geometry



2. $\Gamma(r_{//}, z)$

3.
$$SP_{meas} = \Gamma \otimes SP_{real}$$

inversion

4.
$$SP_{real} = \Gamma^{-1} \otimes SP_{meas}$$

Γ : an operative definition

1. SP broadening
or simplified geometry



2. $\Gamma(r_{//}, z)$

3. $SP_{meas} = \Gamma \otimes SP_{real}$

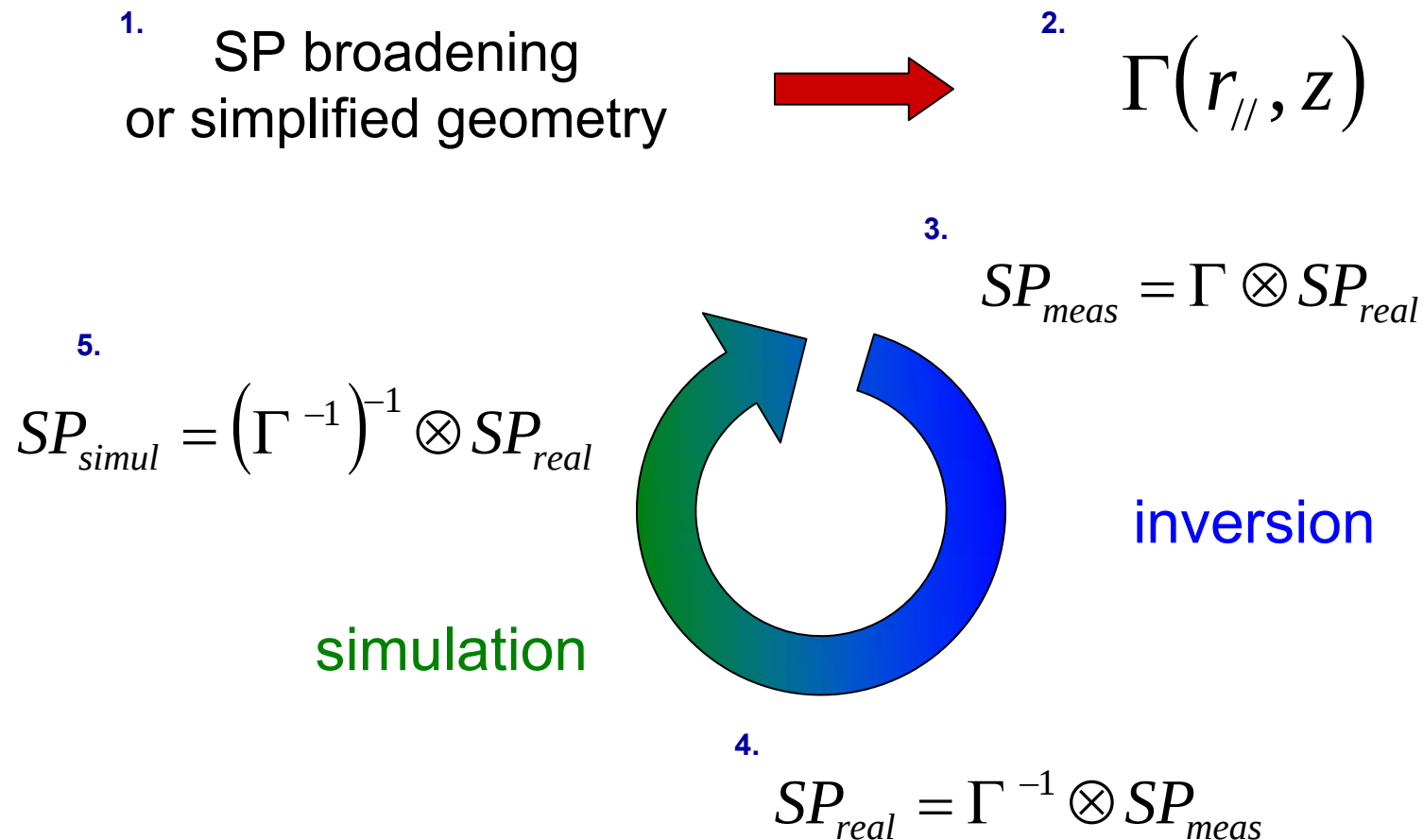
5. $SP_{simul} = (\Gamma^{-1})^{-1} \otimes SP_{real}$

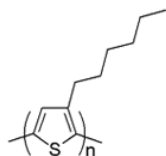
inversion

simulation

4. $SP_{real} = \Gamma^{-1} \otimes SP_{meas}$

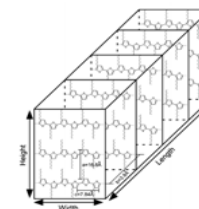
Γ : an operative definition





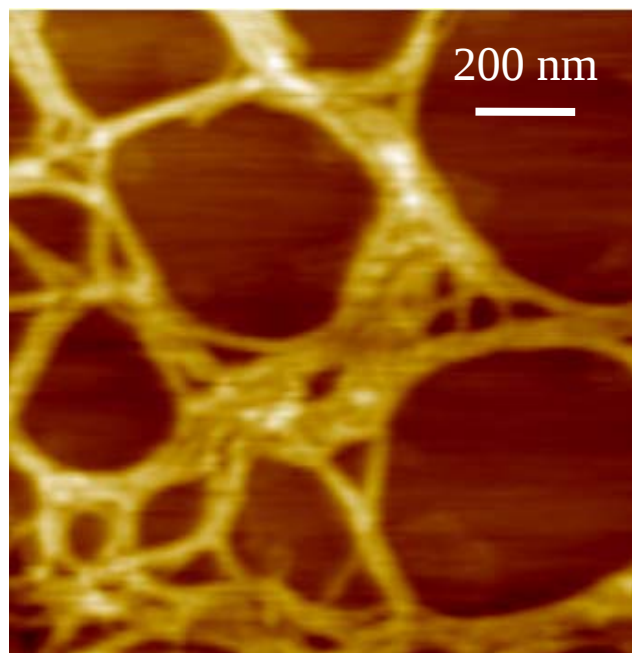
Poly-3-hexylthiophene
(P3HT)

Quasi 1D-systems: P3HT nanofibres on HOPG



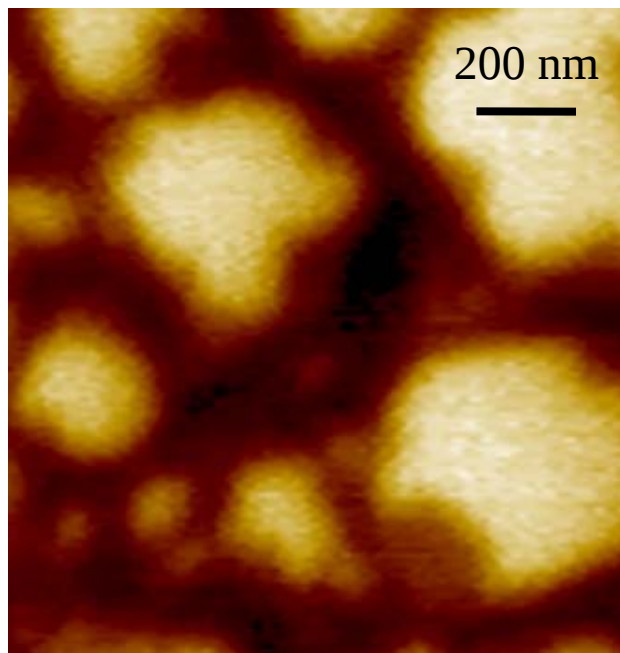
Merlo J.A. et al.,
J. Phys. Chem. **108** (2004), 19169

Topography



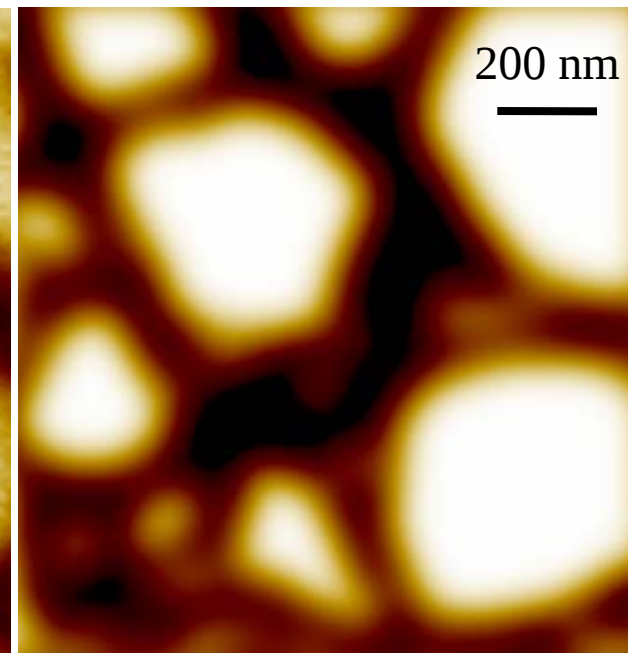
Z range = 10 nm

Measured KPFM

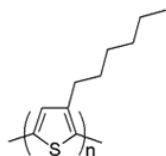


Z range = 180 mV

Simulated KPFM

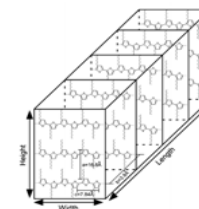


Z range = 180 mV



Poly-3-hexylthiophene
(P3HT)

Quasi 1D-systems: P3HT nanofibres on HOPG

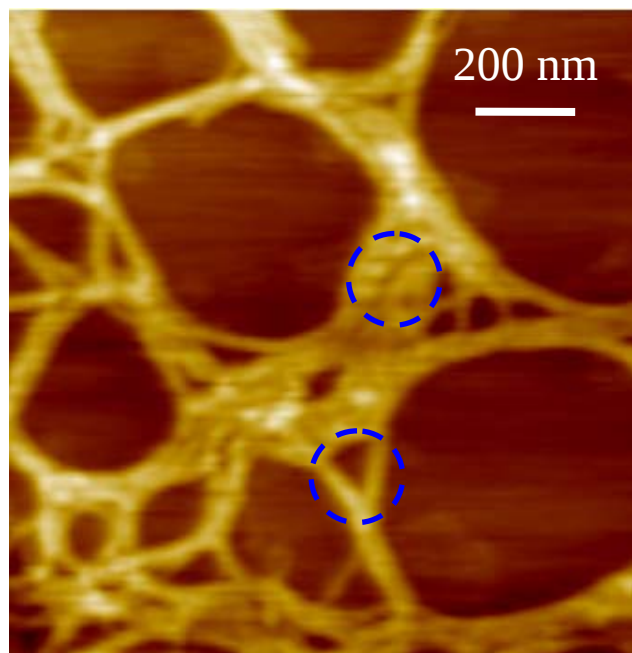


Merlo J.A. et al.,
J. Phys. Chem. **108** (2004), 19169

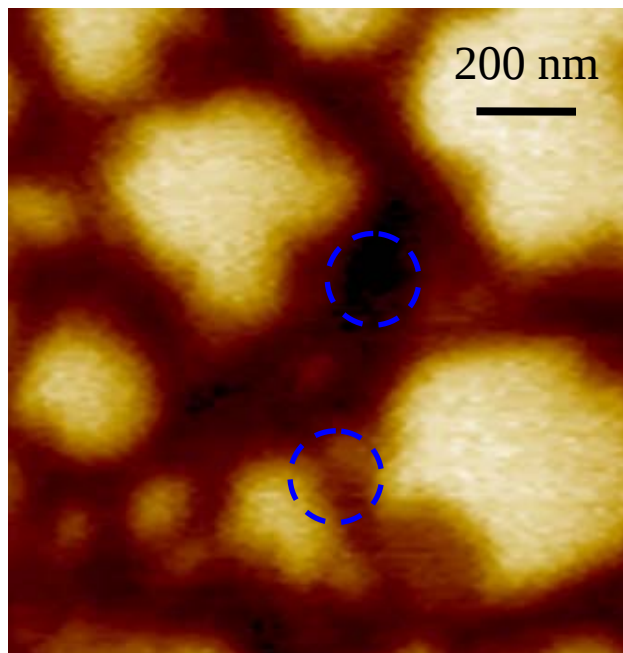
Topography

Measured KPFM

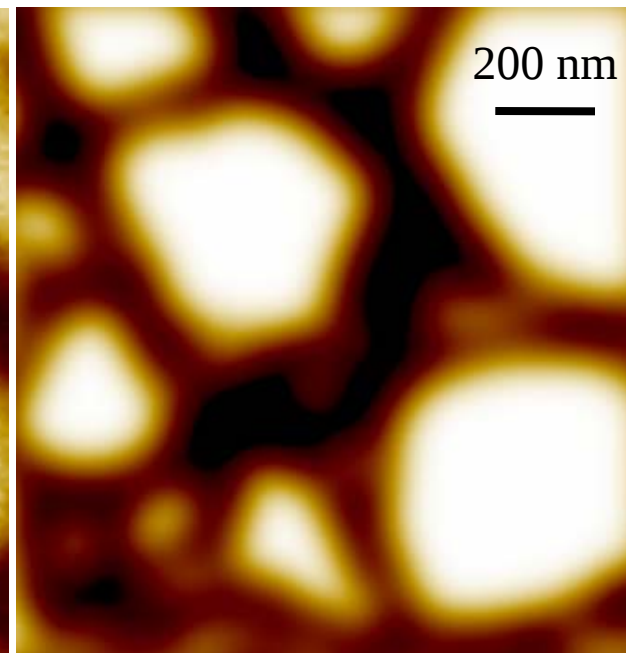
Simulated KPFM



Z range = 10 nm



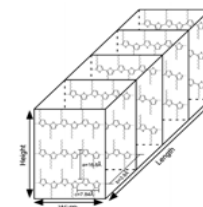
Z range = 180 mV



Z range = 180 mV

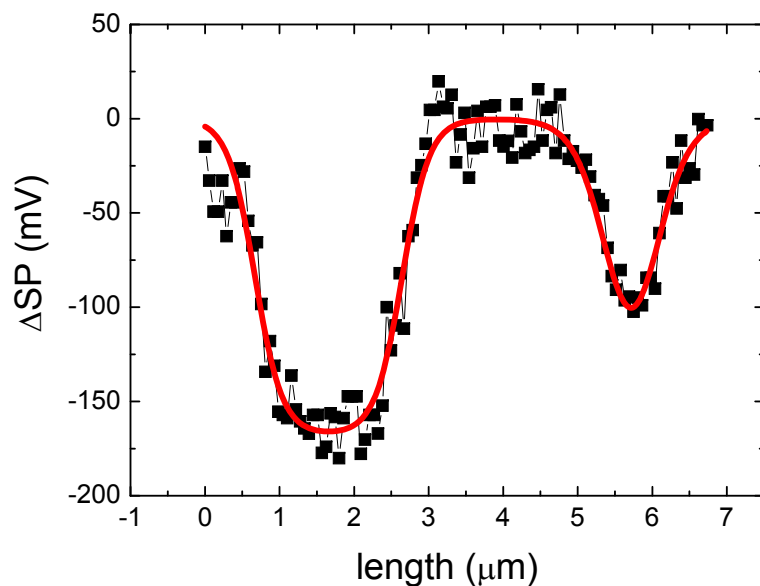
Quasi 1D-systems:

Carbon nanotubes on HOPG



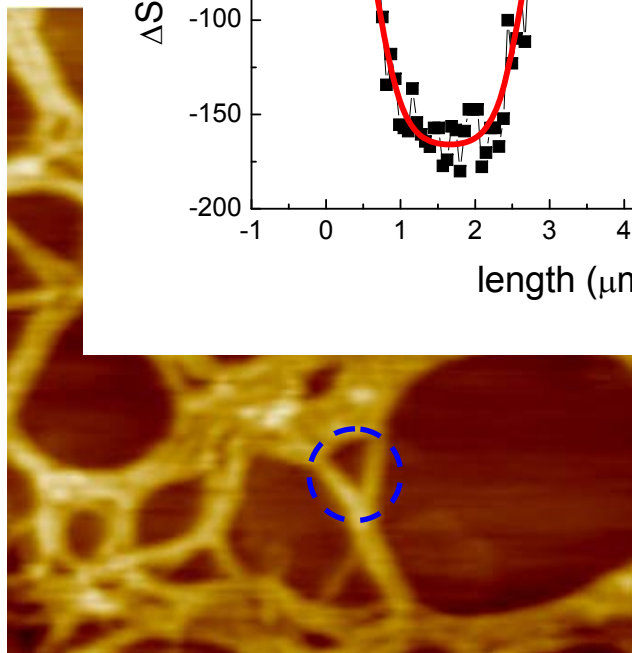
Merlo J.A. et al.,
J. Phys. Chem. **108** (2004), 19169

P

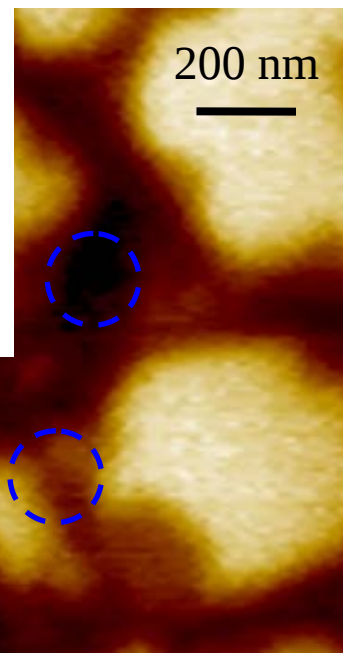


Experimental KPFM

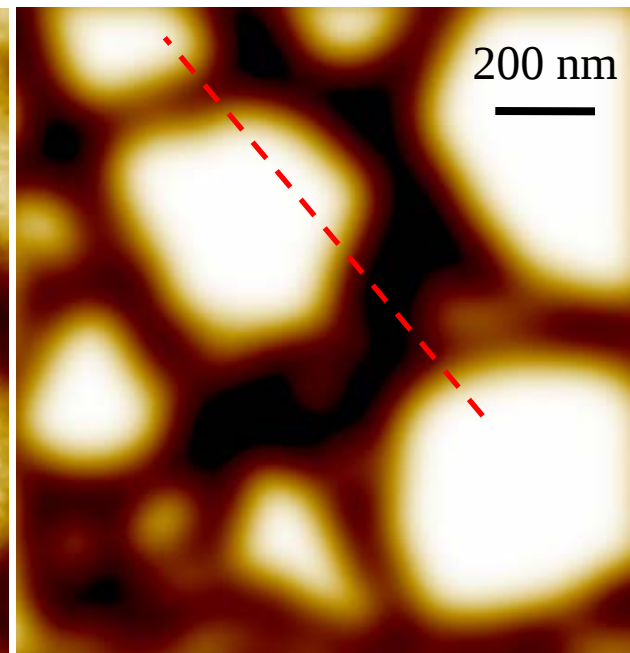
Simulated KPFM



Z range = 10 nm



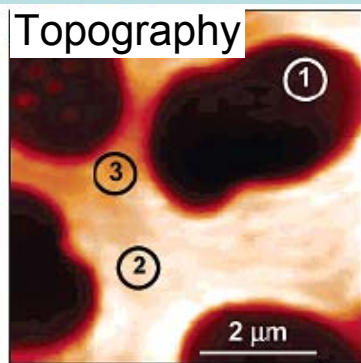
Z range = 180 mV



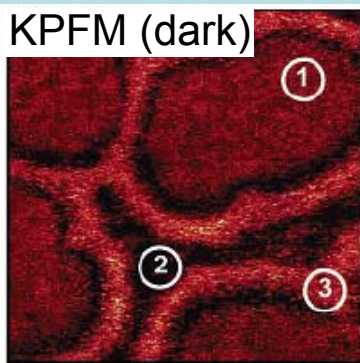
Z range = 180 mV

Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

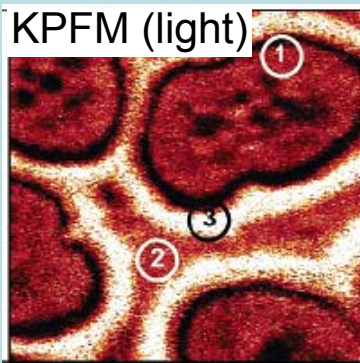
Topography



KPFM (dark)



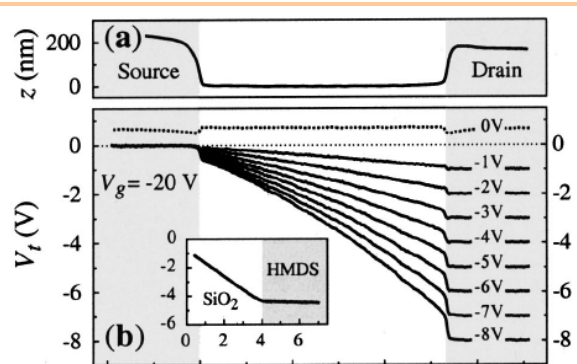
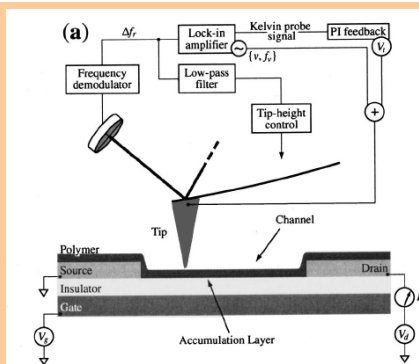
KPFM (light)



Photovoltaic

F8BT/PFB blends

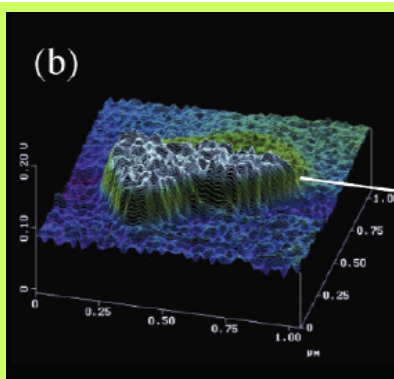
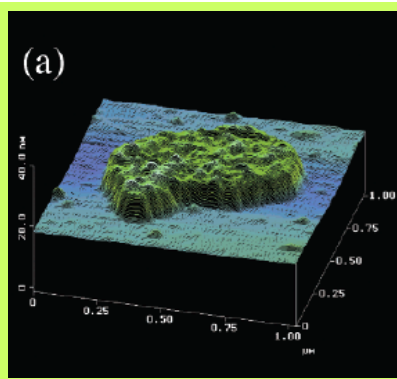
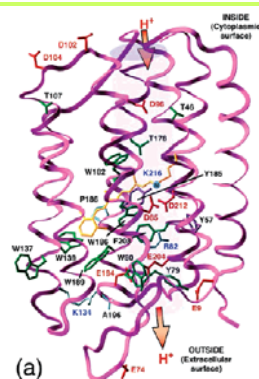
M. Chiesa, L. Burgi, J. Kim, R.H. Friend, H. Sirringhaus,
NanoLetters **5** (2005), 559



Working FET

P3HT thin film

L. Bürgi, H. Sirringhaus, R.H. Friend,
Appl. Phys. Lett. **80** (2002,) 2913

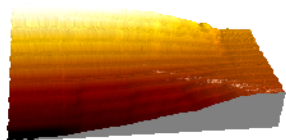


Biology

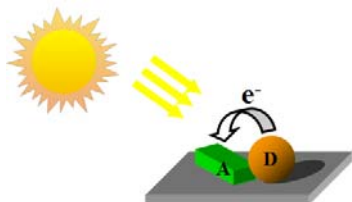
Bacteriorhodopsin Mutant D96N

I. Lee, E. Greenbaum, S. Budy,
J.R. Hillebrecht, R.R. Birge, J.A. Stuart,
J. Phys. Chem. B **110** (2006), 10

What we can measure?



Electrical studies performed on Organic Field-Effect Transistors

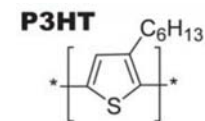
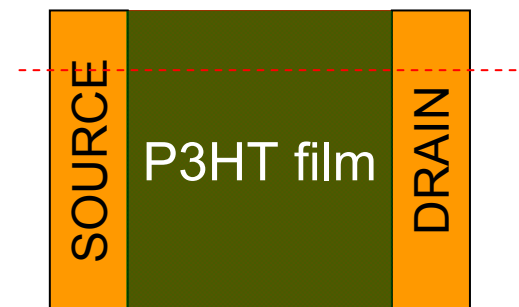
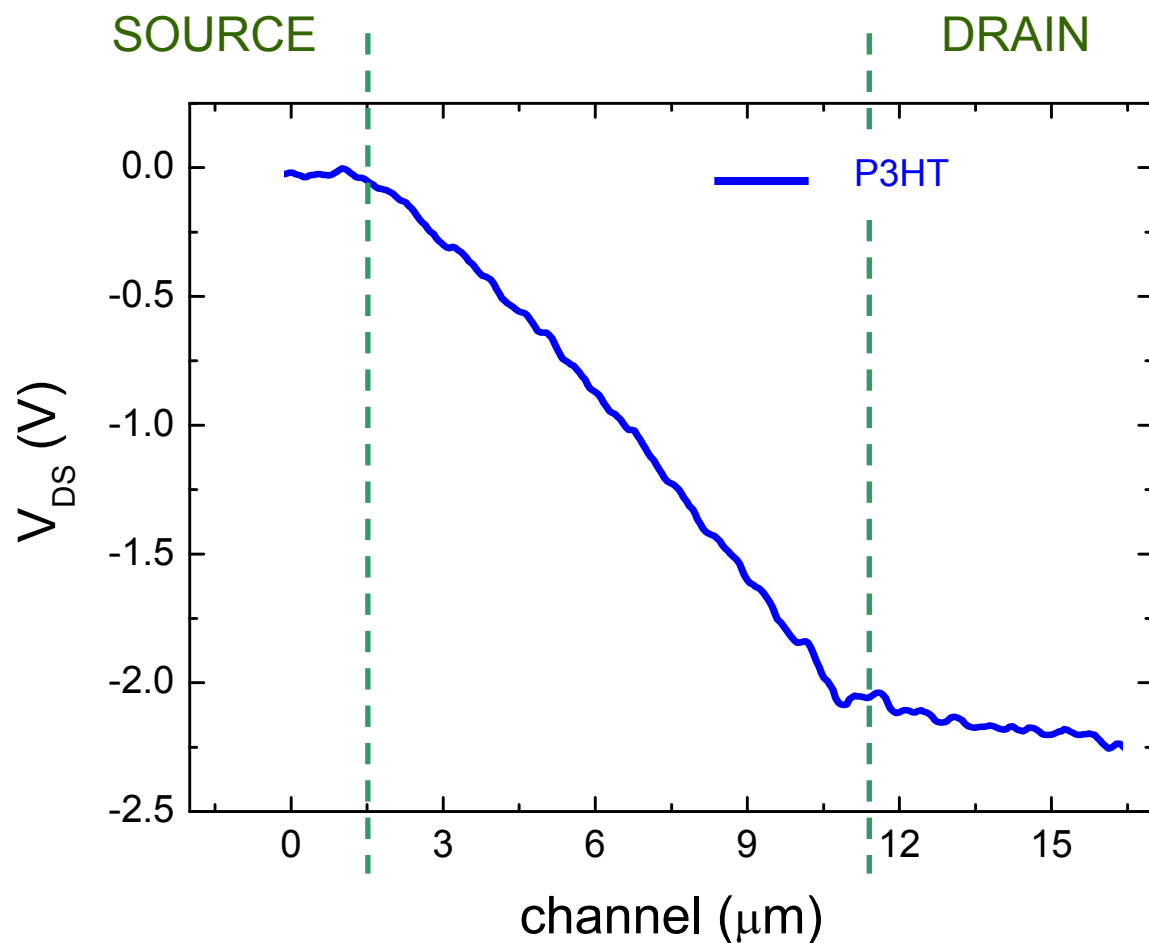


Mapping the photovoltaic activity on the nanometer scale

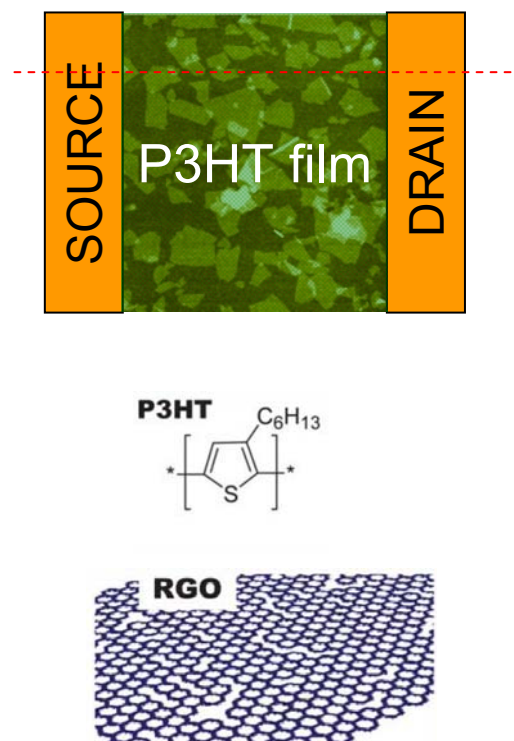
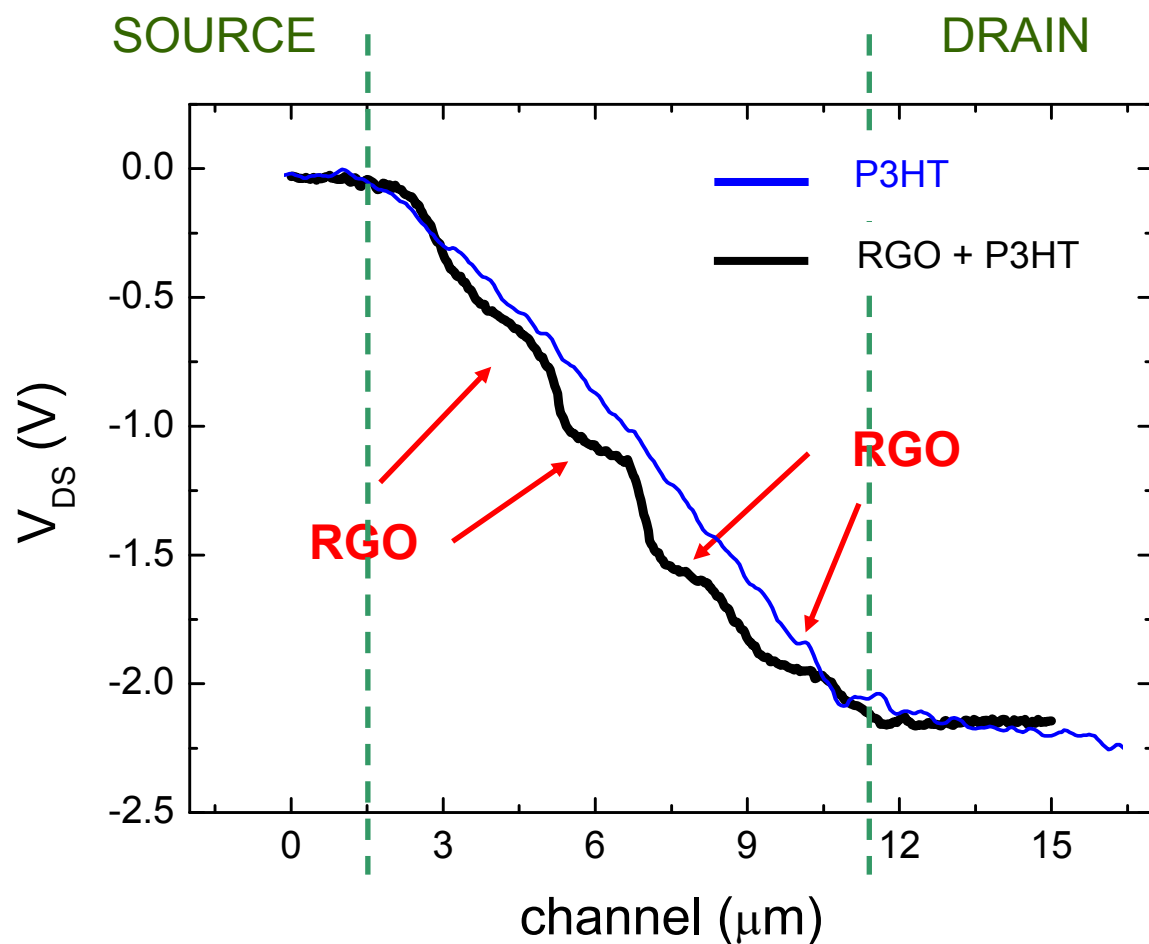


Gold

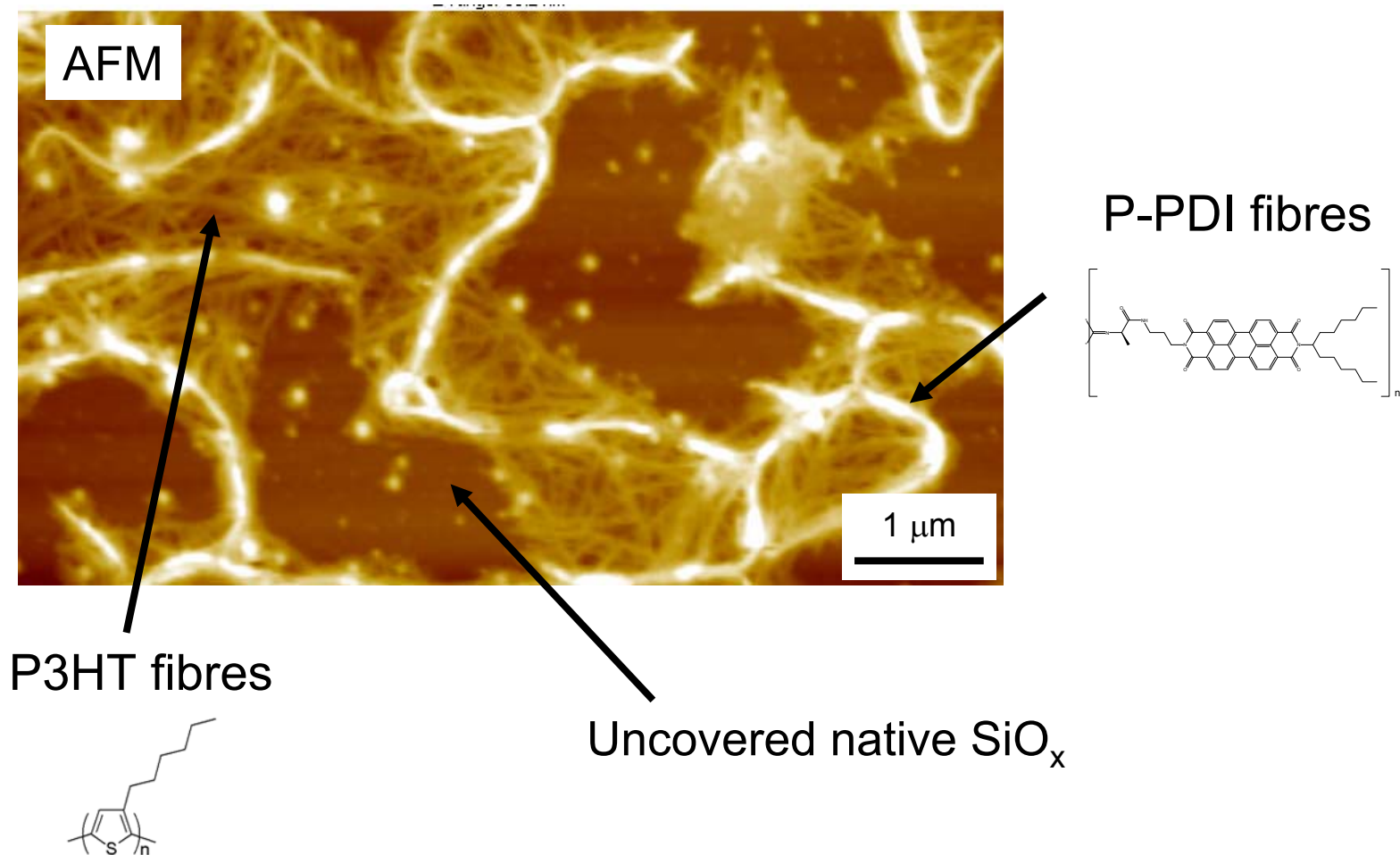
Organic Field-Effect Transistor



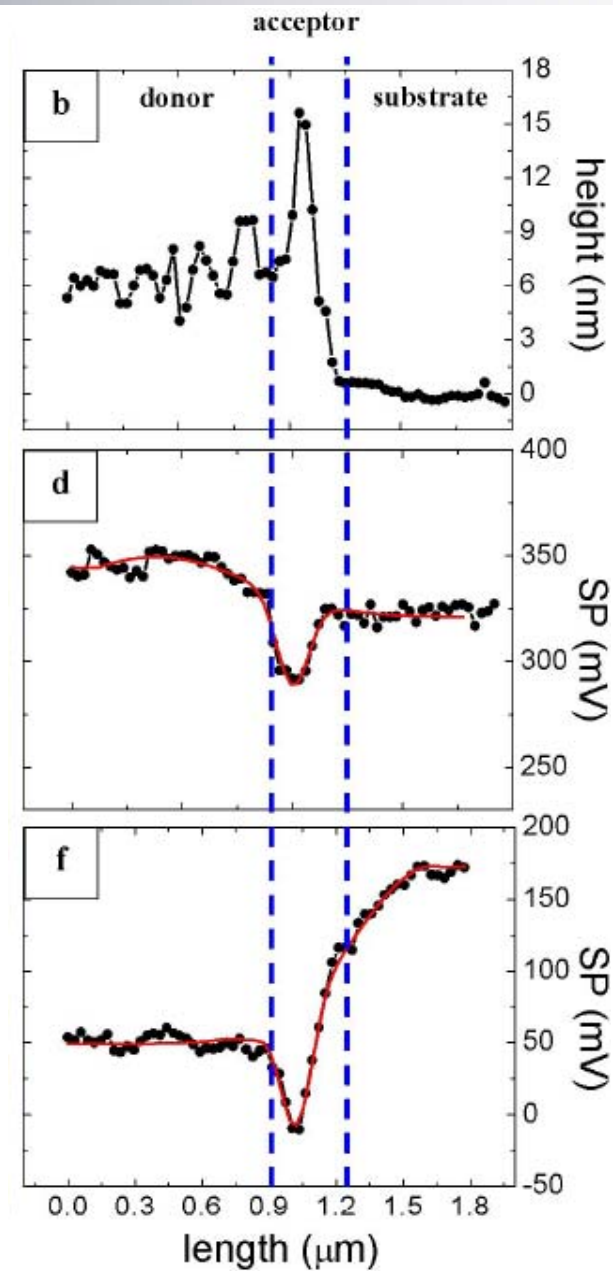
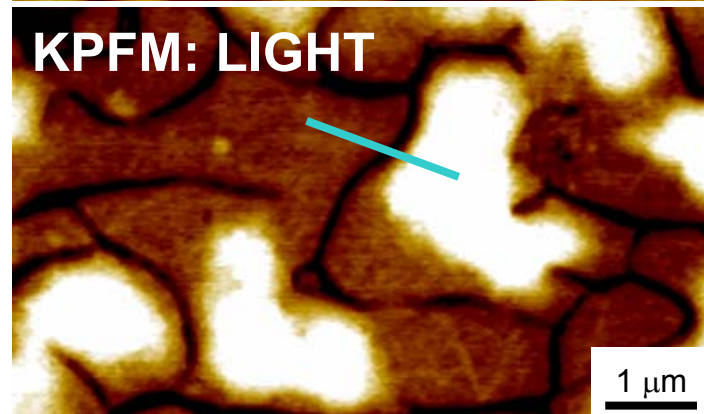
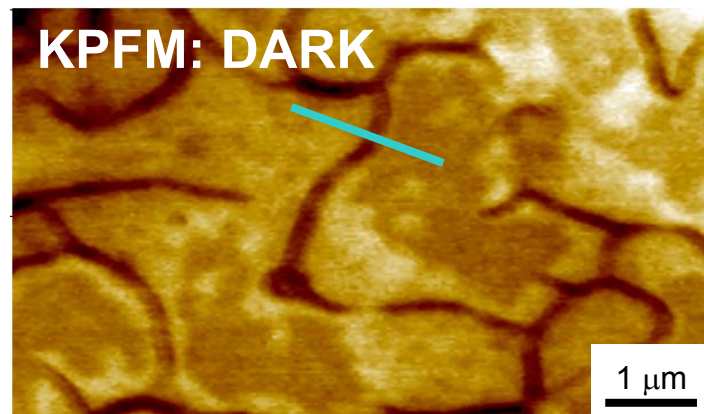
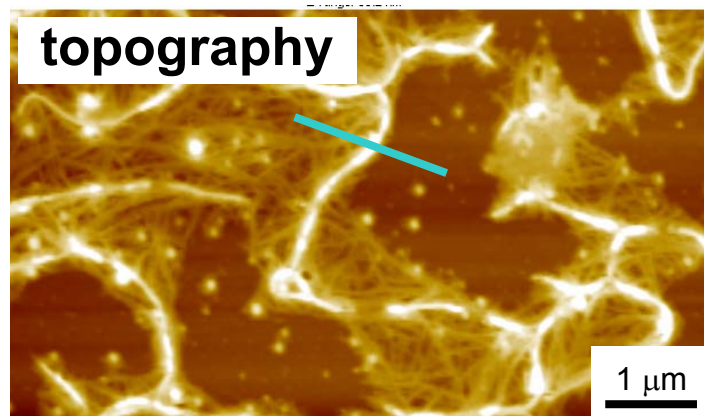
Organic Field-Effect Transistor



Ultra-thin blend of P-PDI/P3HT on Si

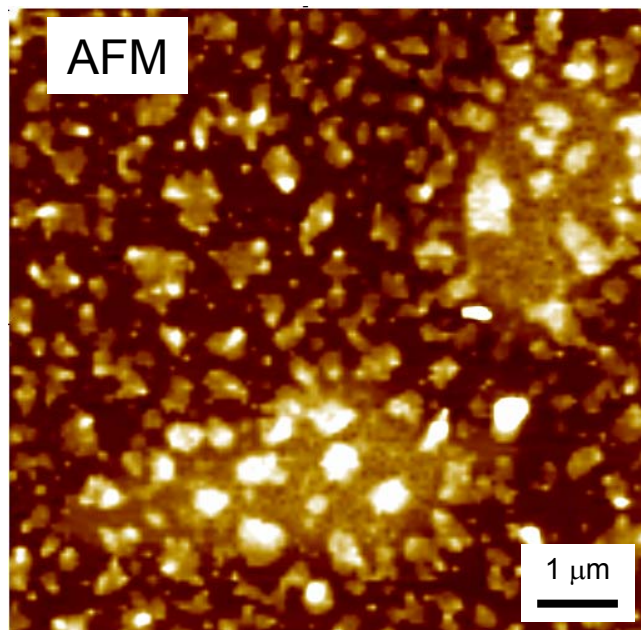
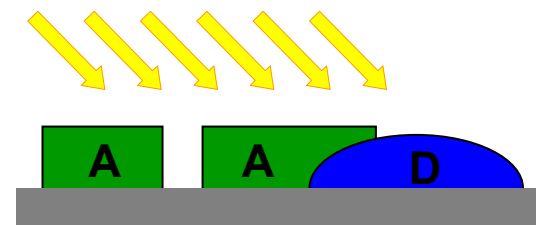
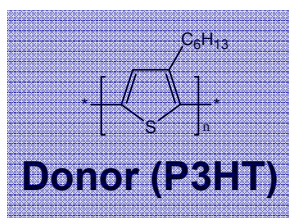
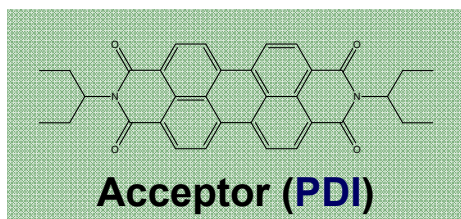


Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

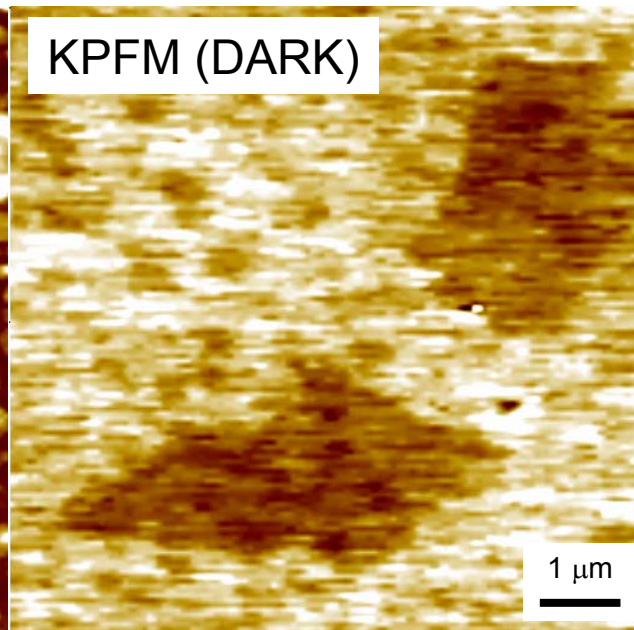


Photovoltaic charge generation
visualized at the nanoscale:
a proof of principle

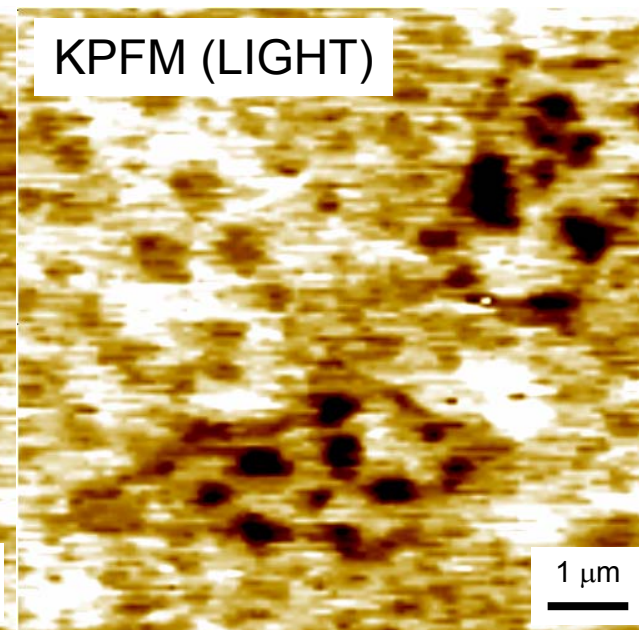
Photovoltaic activity occurring between PDI and P3HT



Z range = 40 nm



Z range = 60 mV



Z range = 60 mV

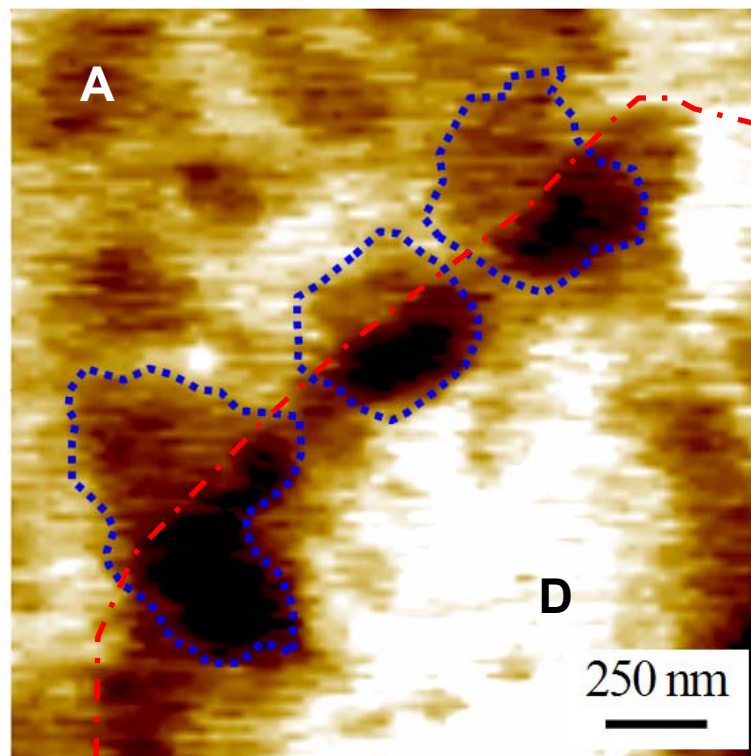
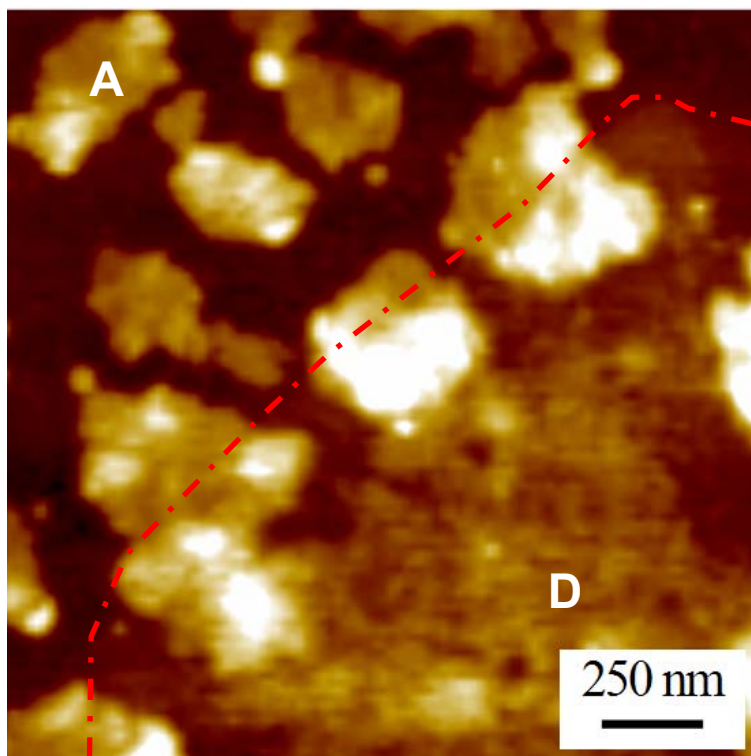
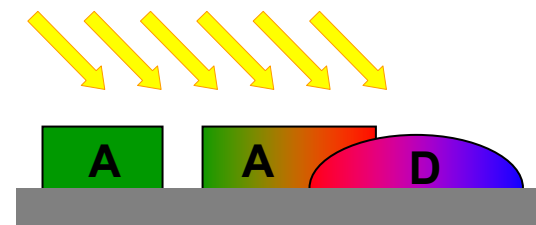
Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

Photovoltaic activity occurring between PDI and P3HT

Table 1. SPs of P3HT and PDI Measured for Sample under Dark and Light Irradiation^a

	SP (mV)		
	P3HT (type III)	PDI (type II)	PDI (type I)
dark	-30 ± 5	-40 ± 5	-12 ± 4
light	-10 ± 5	-90 ± 10	-32 ± 5
dark - light	-20 ± 7	50 ± 11	20 ± 7

^a SPs are given as differences with respect to substrate SP. The error bars are the variances obtained by averaging over all the collected measurements.



Photovoltaic activity occurring between PDI and P3HT

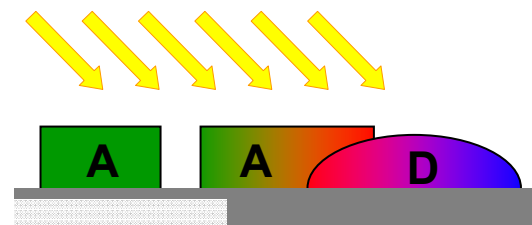
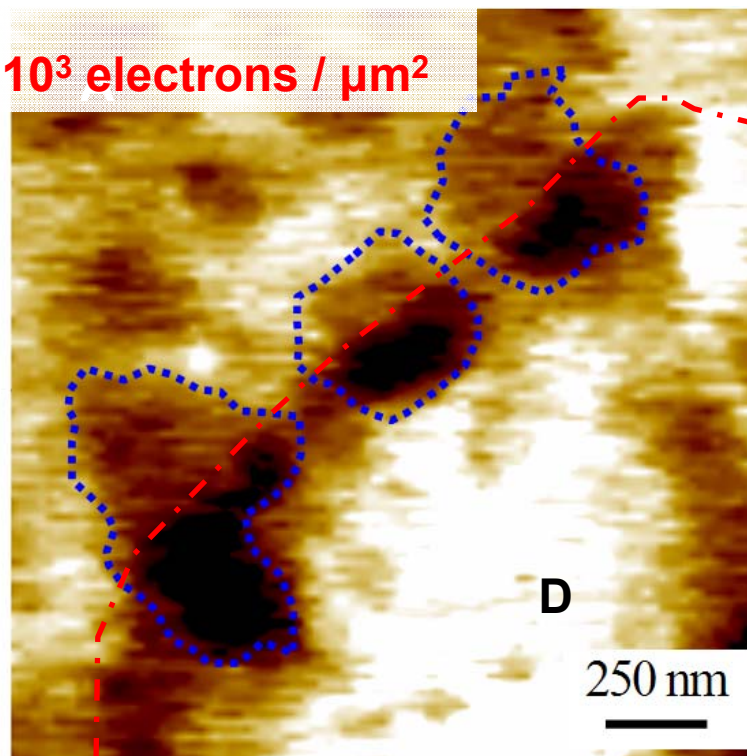
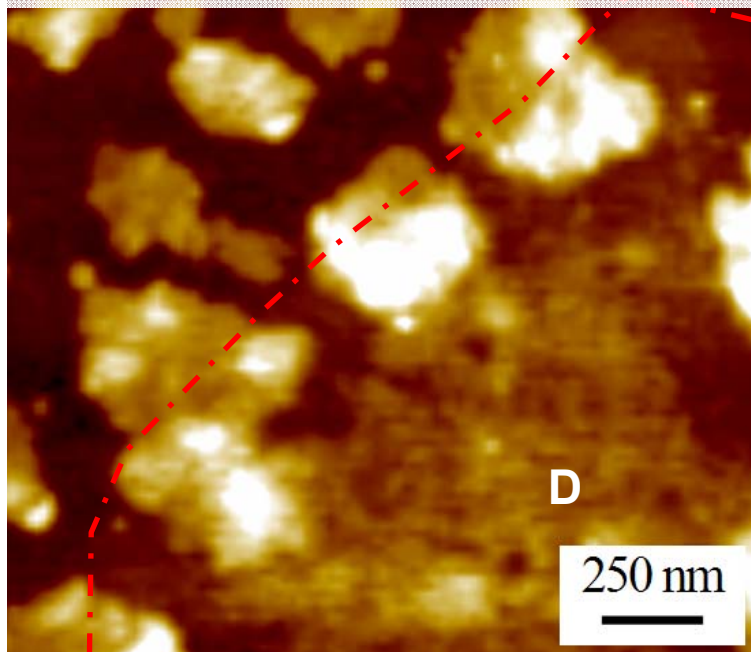
Table 1. SPs of P3HT and PDI Measured for Sample under Dark and Light Irradiation^a

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dark – light	-20 ± 7	50 ± 11	20 ± 7

^a SPs are given as differences with respect to the dark state. The error bars are the variances obtained by averaging measurements.

$$\Delta Q = \pi \epsilon d \Delta V$$

Photo-induced charges at interface = ca 10^3 electrons / μm^2



Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

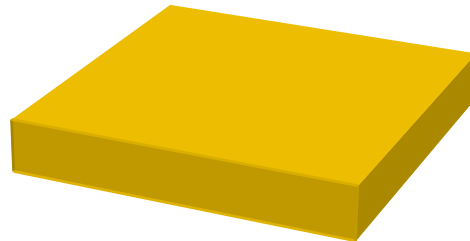
GOLD



Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

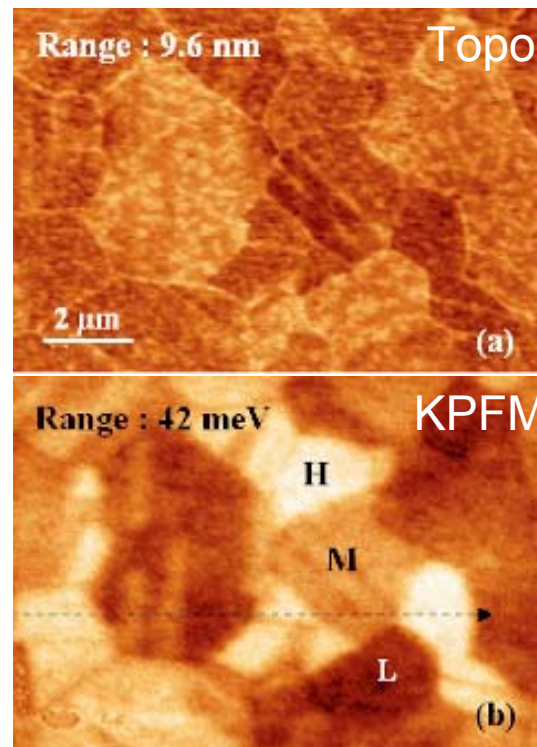
Increasing the complexity

Ideal case



Flat
Perfect reflection
etc

High controlled case

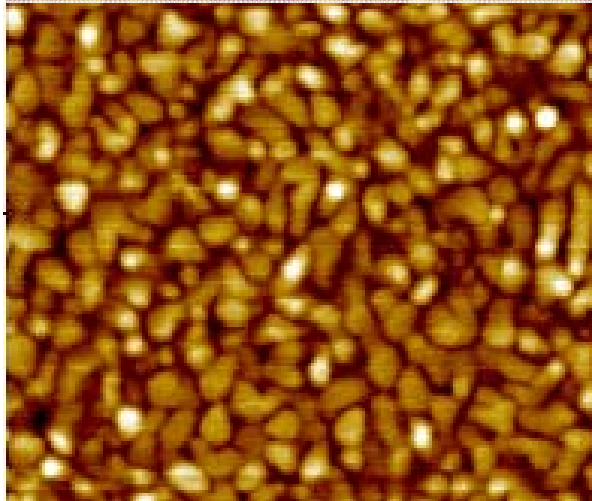


“Typical” case



Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

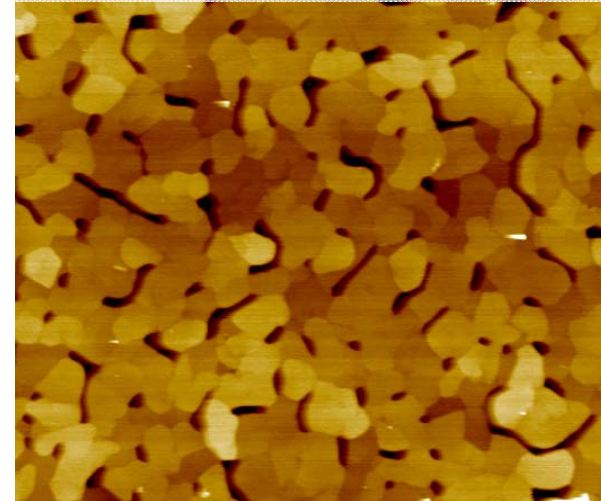
Gold evaporated on glass



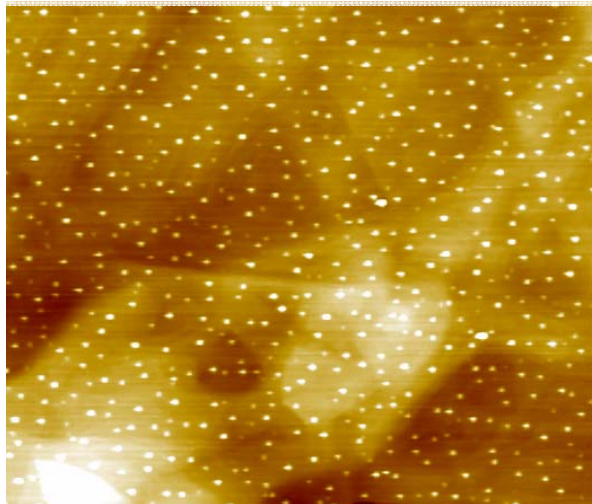
200 nm

substrate

Gold evaporated on glass

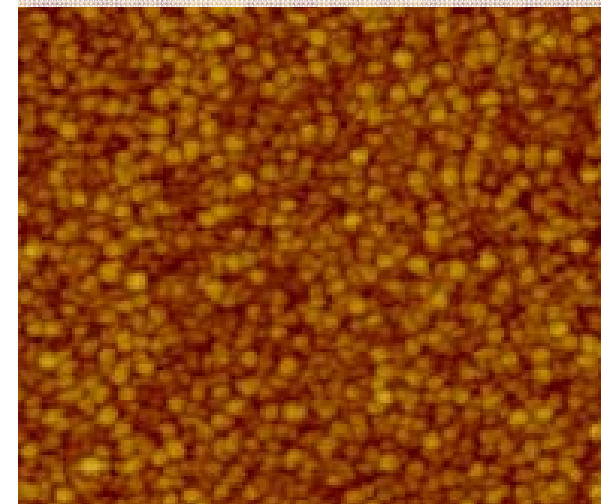


Gold evaporated on mica



AFM size
 $2.56 \times 2.56 \mu\text{m}^2$

Gold sputtered on glass



SURFACE POTENTIAL “ROUGHNESS”

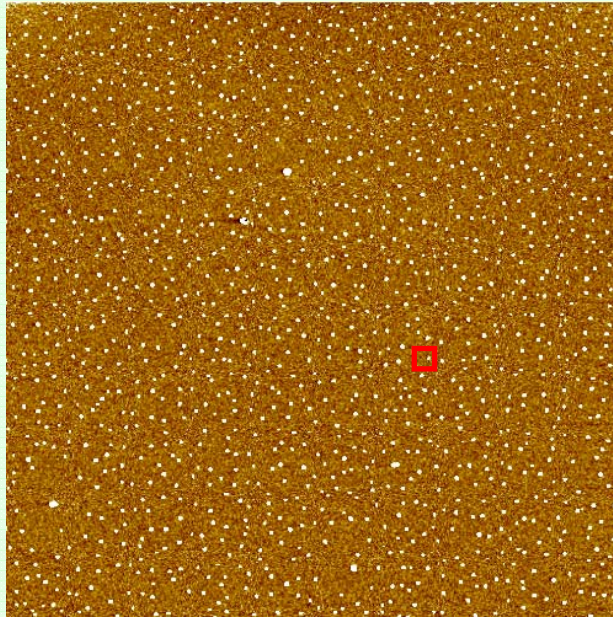
A multi-scale, time-dependent parameter

Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

AFM

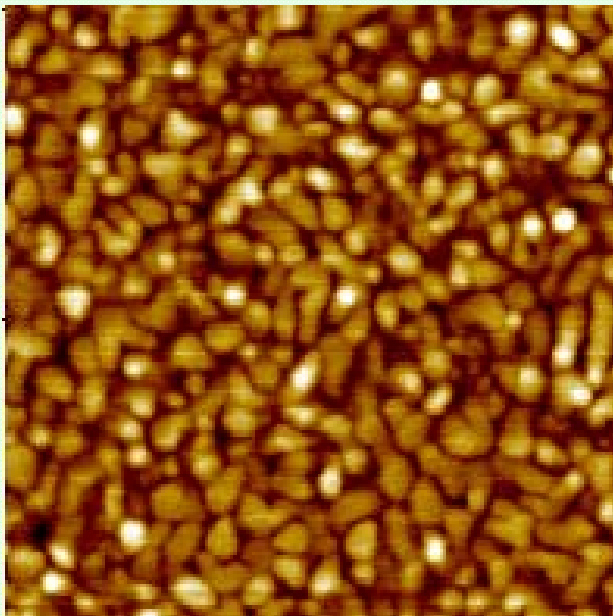
Lat. size
81.92 μm

Z range
= 12 nm



Lat. size
2.56 μm

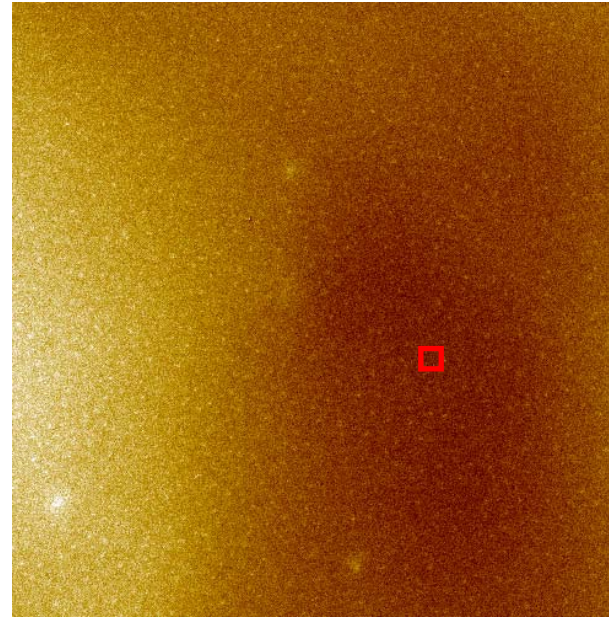
Z range
= 12 nm



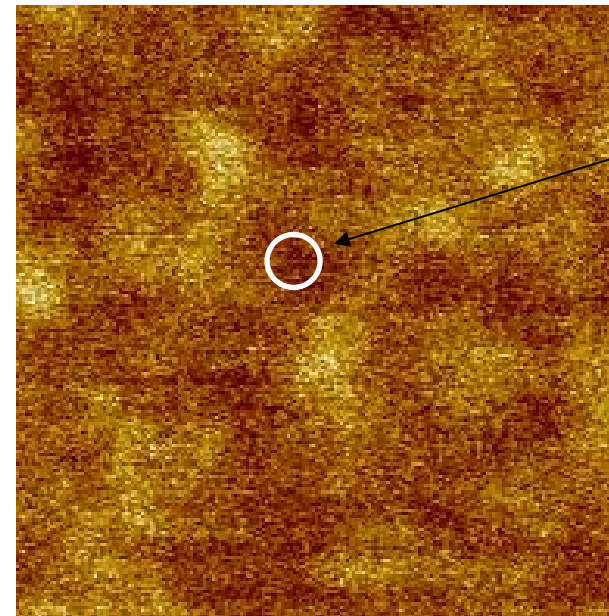
KPFM

Lat. size
81.92 μm

Z range
= 50 mV



Effective area



Lat. size
2.56 μm

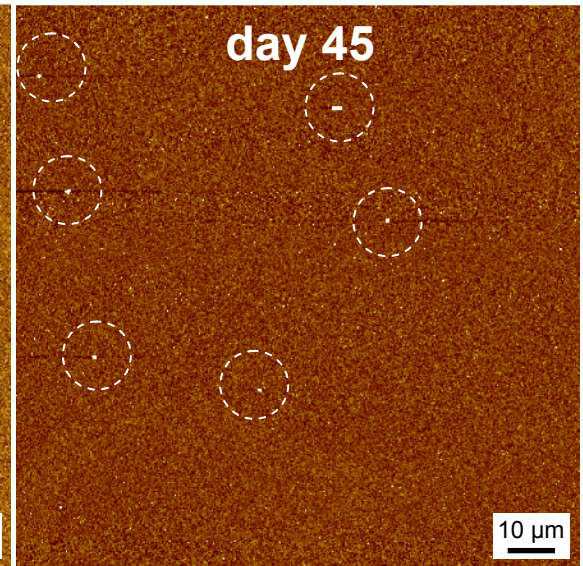
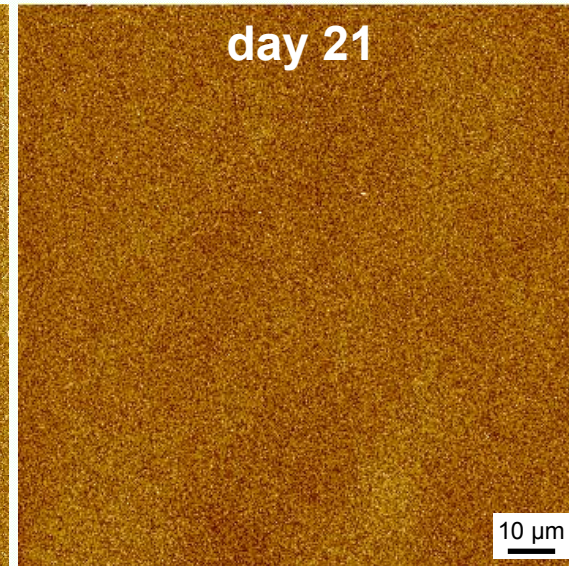
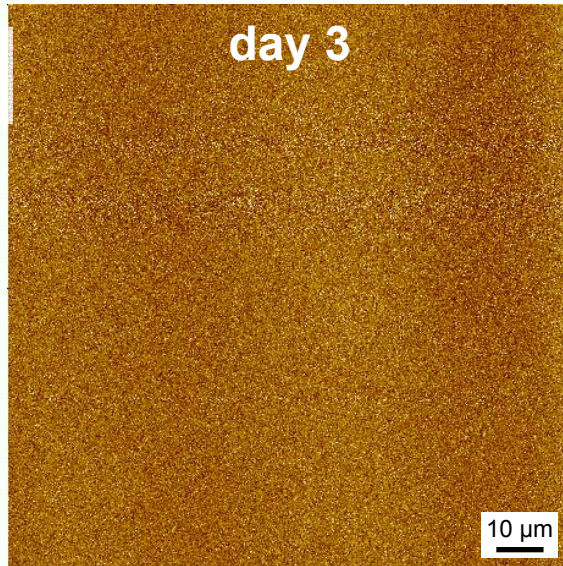
Z range
= 12 mV

AGING EFFECTS

Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

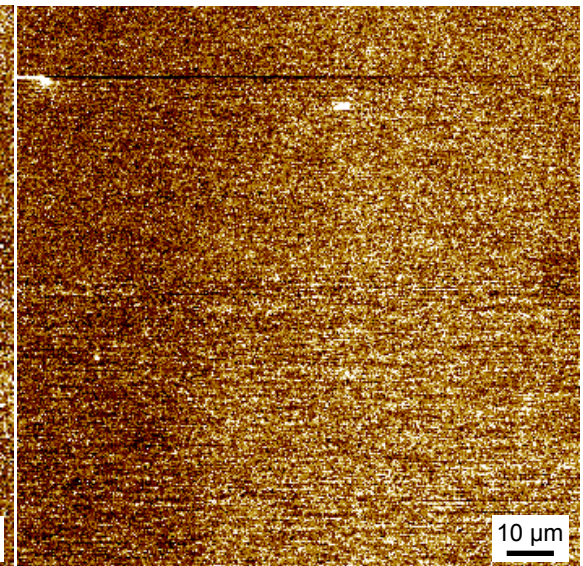
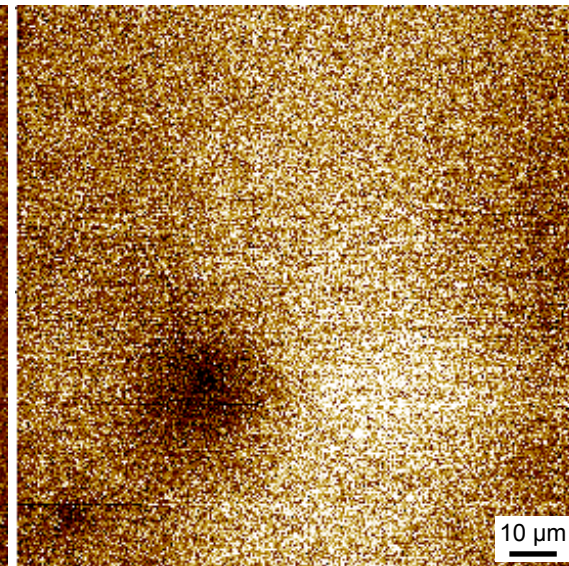
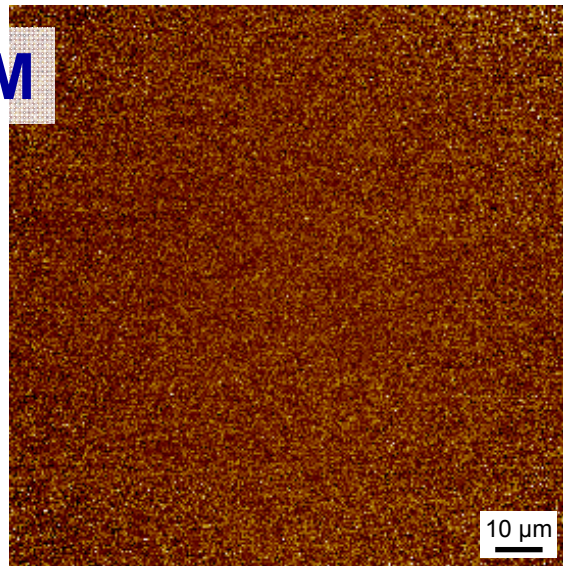
AFM

Z range
= 2 nm



KPFM

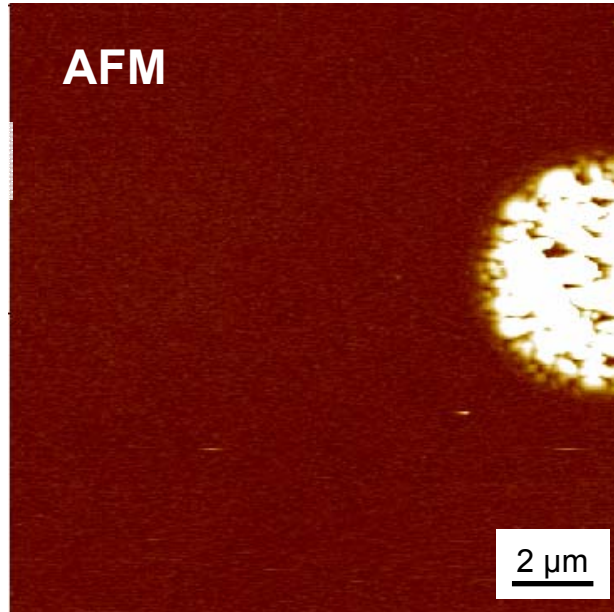
Z range
= 15 mV



Electrical characterization and nanoscale surface morphology with Scanning Probe Microscopies

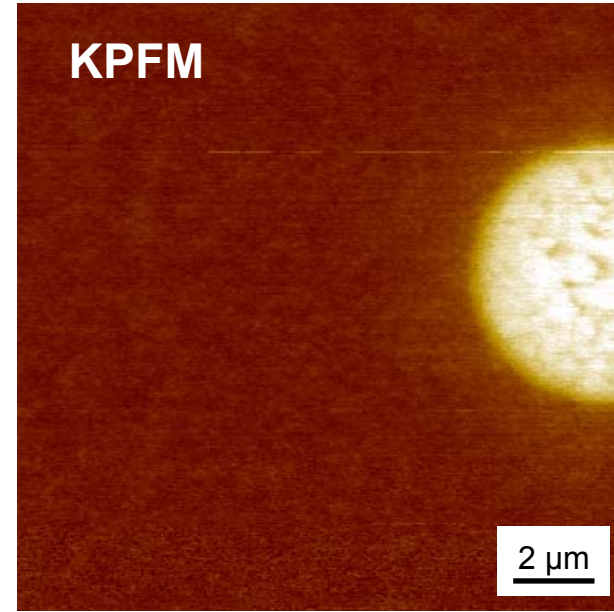
CLUSTERS

AFM



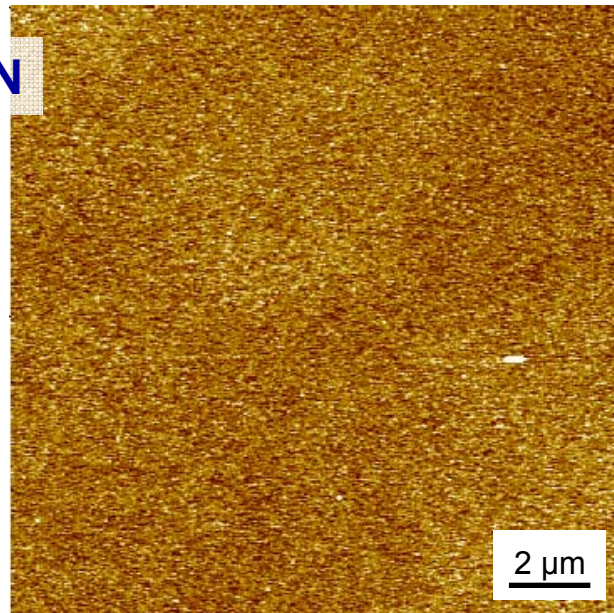
Z-range = 30 nm

KPFM

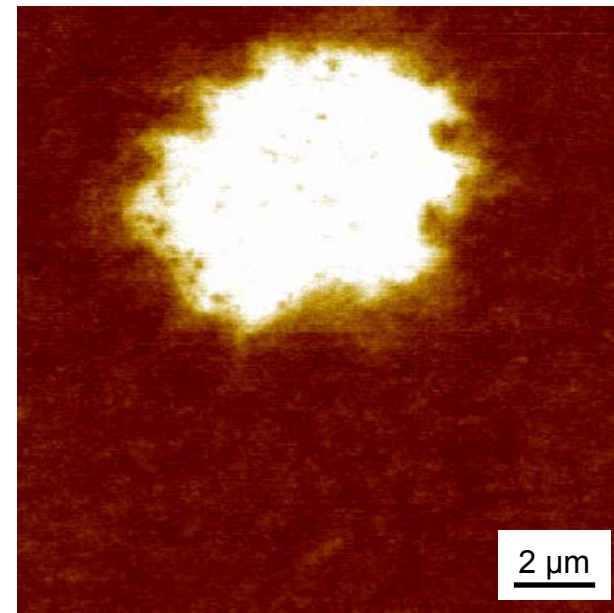


Z-range = 160 mV

ADSORPTION



Z-range = 10 nm



Z-range = 100 mV

Outlooks

- SPMs are suitable techniques to explore nanoscale
- Quantitative analysis of SPM images: handle with care
- Gold surface example

One name for several surfaces

Roughness (and patches) are multi-scale parameters

